



## 8th International Symposium on Growth of III-Nitrides

November 9-12, 2025 | NCKU, Tainan, Taiwan

Handbook



國立成功大學  
National Cheng Kung University



NSTC 國家科學及技術委員會  
National Science and Technology Council



國立陽明交通大學電子研究所  
Institute of Electronics,  
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# ISGN-8

November 9-12, 2025

NCKU, Taiwan



# 8th International Symposium on Growth of III-Nitrides (ISGN-8)

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The 8th International Symposium on Growth of III-Nitrides (ISGN-8) is a biennial conference rotating among host countries, focusing on advances in the growth of III-nitride bulk crystals, thin films, and nanostructures. Since its inception in 2006 in Sweden, ISGN has been held across Europe, Asia, and the US. ISGN-8, originally planned for 2020 in San Diego, was canceled due to COVID-19. The symposium resumes in 2025 and takes place from **November 9 to November 12, 2025**, at National Cheng Kung University (NCKU) in Tainan, Taiwan.

This year, ISGN-8 comprises 10 parallel sessions and 1 special session:

- S1. III-N Bulk Crystal Growth
- S2. III-N Epitaxial Growth Techniques
- S3. III-N Ternary and Quaternary Alloys
- S4. III-N Nanostructures and 2D Materials
- S5. III-N Heterostructure Characterization
- S6. III-N Defect Control and Surface Effects
- S7. III-N Optical and Electrical Properties
- S8. III-N Device Modeling and Simulation
- S9. III-N Spin-related Phenomena
- S10. III-N Devices—FETs, LEDs, and Lasers
- Special Session. Ultrawide-bandgap materials and devices

**For more information about ISGN-8, please visit:**



# Agenda

Day 0 - November 9 (Sunday)	
Time/Room	多功能廳 Multifunction Room
18:00-20:30	Networking Meeting (Reception) <b>(Invitation Only)</b>



## Day 1 – November 10 (Monday)

08:30-17:00	Registration	
Time/Room	第一演講室 1st Lecture Room	
09:00-09:20	ISGN-8 Opening Ceremony	
09:20-10:10	Plenary Session 1: Prof. Zetian Mi Presider: Prof. Ray-Hua Horng 洪瑞華	
10:10-10:20	Coffee Break	
10:20-11:10	Plenary Session 2: Prof. Kei May Lau 劉紀美 Presider: Prof. Ray-Hua Horng 洪瑞華	
11:10-12:00	Plenary Session 3: Prof. Elison Matioli Presider: Prof. Ray-Hua Horng 洪瑞華	
12:00-13:00	多功能廳 Multifunction Room	
	Lunch	
	Exhibitor Seminar - Orbray Co., Ltd. The Cutting Edge and Future of Lab-Grown Diamonds	
Time/Room	第二演講室 2nd Lecture Room	第三演講室 3rd Lecture Room
Session	S1. III-N Bulk Crystal Growth S5. III-N Heterostructure Characterization	S4. III-N Nanostructures and 2D Materials S9. III-N Spin-related Phenomena
Presider	Prof. Ming-Chi Mitch Chou 周明奇 Dr. Michał Boćkowski	Prof. Yu-Hsun Chou 周昱薰 Prof. Jesús Zúñiga Pérez
13:00-13:30	Invited Talk- Dr. Michał Boćkowski	Invited Talk- Prof. Jesús Zúñiga Pérez
13:30-13:45	Oral Presentation (0107)	Invited Talk-
13:45-14:00	Oral Presentation (0064)	Dr. Bernard Gil
14:00-14:15	Oral Presentation (0065)	Oral Presentation (0041)
14:15-14:30	Oral Presentation (0087)	Oral Presentation (0028)
14:30-14:45	Oral Presentation (0096)	Oral Presentation (0118)
14:45-15:00	Coffee Break	
Time/Room	第二演講室 2nd Lecture Room	第三演講室 3rd Lecture Room
Session	S1. III-N Bulk Crystal Growth S5. III-N Heterostructure Characterization	S6. III-N Defect Control and Surface Effects
Presider	Prof. Ming-Chi Mitch Chou 周明奇 Dr. Michał Boćkowski	Prof. Hsiang-Chen Wang 王祥辰 Prof. Che-Hao Liao 廖哲浩
15:00-15:15	Oral Presentation (0081)	Invited Talk-
15:15-15:30	Oral Presentation (0018)	Prof. Chris G. Van de Walle
15:30-15:45	Invited Talk-	Oral Presentation (0007)
15:45-16:00	Prof. Frank Bertram	Oral Presentation (0029)
16:00-16:15	Oral Presentation (0062)	Oral Presentation (0046)
16:15-16:30	Oral Presentation (0003)	Oral Presentation (0112)
16:30-16:45	Oral Presentation (0048)	Oral Presentation (0085)
16:45-17:00	Oral Presentation (0104)	Oral Presentation (0024)
18:00-20:30	IAC Meeting (Invitation Only)	

**Day 2 – November 11 (Tuesday)**

08:00-17:00	Registration			
Time/Room	第一演講室 1st Lecture Room			
08:30-09:20	Plenary Session 4: Prof. Jen-Inn Chyi 蔡振瀛 Presider: Prof. Yuh-Renn Wu 吳育任			
09:20-10:10	Plenary Session 5: Dr. Hideki Hirayama 平山 秀樹 Presider: Prof. Yuh-Renn Wu 吳育任			
10:10-10:20	Coffee Break			
10:20-11:10	Plenary Session 6: Prof. James S. Speck Presider: Prof. Yuh-Renn Wu 吳育任			
11:10-12:00	Plenary Session 7: Prof. Debdeep Jena Presider: Prof. Yuh-Renn Wu 吳育任			
12:00-13:00	Lunch @ Multifunction Room 多功能廳			
Time/Room	第二演講室 2nd Lecture Room	第三演講室 3rd Lecture Room	多功能廳 Multifunction Room	
Session	S3. III-N Ternary and Quaternary Alloys	S8. III-N Device Modeling and Simulation	Posters can be posted	
Presider	Prof. Chia-Yen Huang 黃嘉彥 Prof. Mitsuru Funato 船戶 充	Prof. Ya-Ju Lee 李亞儒 Prof. Yoshihiro Kangawa 寒川 義裕		
13:00-13:30	Invited Talk- Prof. Mitsuru Funato	Invited Talk- Prof. Yoshihiro Kangawa		
13:30-13:45	Oral Presentation (0098)	Invited Talk- Dr. Muhammad Ajmal Khan		
13:45-14:00	Oral Presentation (0026)			
14:00-14:15	Oral Presentation (0068)	Oral Presentation (0042)		
14:15-14:30	Oral Presentation (0092)	Oral Presentation (0110)		
14:30-14:45	Oral Presentation (0109)	Oral Presentation (0119)		
14:45-15:00	Coffee Break			
Time/Room	第二演講室 2nd Lecture Room	第三演講室 3rd Lecture Room		多功能廳 Multifunction Room
Session	S2. III-N Epitaxial Growth Techniques	S7. III-N Optical and Electrical Properties	Refreshments will be served	
Presider	Prof. Chun-Kai Wang 王俊凱 Prof. Hideto Miyake 三宅 秀人	Prof. Hsin-Chieh Yu 尤信介 Prof. Chan-Shan Yang 楊承山		
15:00-15:30	Invited Talk- Prof. Hideto Miyake	Invited Talk- Prof. Yong-Hoon Cho	Poster Session	
15:30-15:45	Oral Presentation (0108)	Invited Talk- Dr. Sai Charan Vanjari		
15:45-16:00	Oral Presentation (0073)			
16:00-16:15	Oral Presentation (0027)	Oral Presentation (0040)		
16:15-16:30	Oral Presentation (0074)	Oral Presentation (0012)		
16:30-16:45	Oral Presentation (0025)	Oral Presentation (0106)		
16:45-17:00	Oral Presentation (0030)	Oral Presentation (0066)		
17:00-17:15	Oral Presentation (0138)	Oral Presentation (0139)		
18:00-20:30	Banquet @ Far Eastern Grand Ballroom, Shangri-La Far Eastern, Tainan 台南遠東香格里拉 遠東宴會廳			

Day 3 – November 12 (Wednesday)		
08:00-09:15	Registration	
Time/Room	第一演講室 1st Lecture Room	
08:25-09:15	Plenary Session 8: Prof. Xiuling Li Presider: Prof. Wei-Chih Lai 賴韋志	
Time/Room	第二演講室 2nd Lecture Room	第三演講室 3rd Lecture Room
09:15-11:00	Refreshments will be arranged in parallel	
Session	Special Session. Ultrawide-bandgap materials and devices	S10. III-N Devices—FETs, LEDs, and Lasers
Presider	Prof. Hsin-Ying Lee 李欣縈 Prof. Sheng-Po Chang 張勝博	Prof. Zhi-Ting Ye 葉志庭 Prof. Tetsuya Takeuchi 竹內 哲也
09:15-09:45	Invited Talk- Prof. Masataka Higashiwaki	Invited Talk- Prof. Tetsuya Takeuchi
09:45-10:00	Invited Talk- Prof. Okhyun Nam	Oral Presentation (0088)
10:00-10:15		Oral Presentation (0020)
10:15-10:30	Oral Presentation (0032)	Oral Presentation (0089)
10:30-10:45	Oral Presentation (0063)	Oral Presentation (0061)
10:45-11:00	Oral Presentation (0072)	Oral Presentation (0117)
11:00-11:15	Oral Presentation (0039)	Oral Presentation (0079)
11:15-11:30	Oral Presentation (0058)	Oral Presentation (0137)
Time/Room	第一演講室 1st Lecture Room	
11:35-12:00	ISGN-8 Closing and Iwińska Award Ceremony	
12:00	Lunch	
12:30-17:10	Free Tainan City Tour Limited to 35 participants (pre-registered online participants only).	

# ISGN-8 Map



## National Cheng Kung University Campus Map

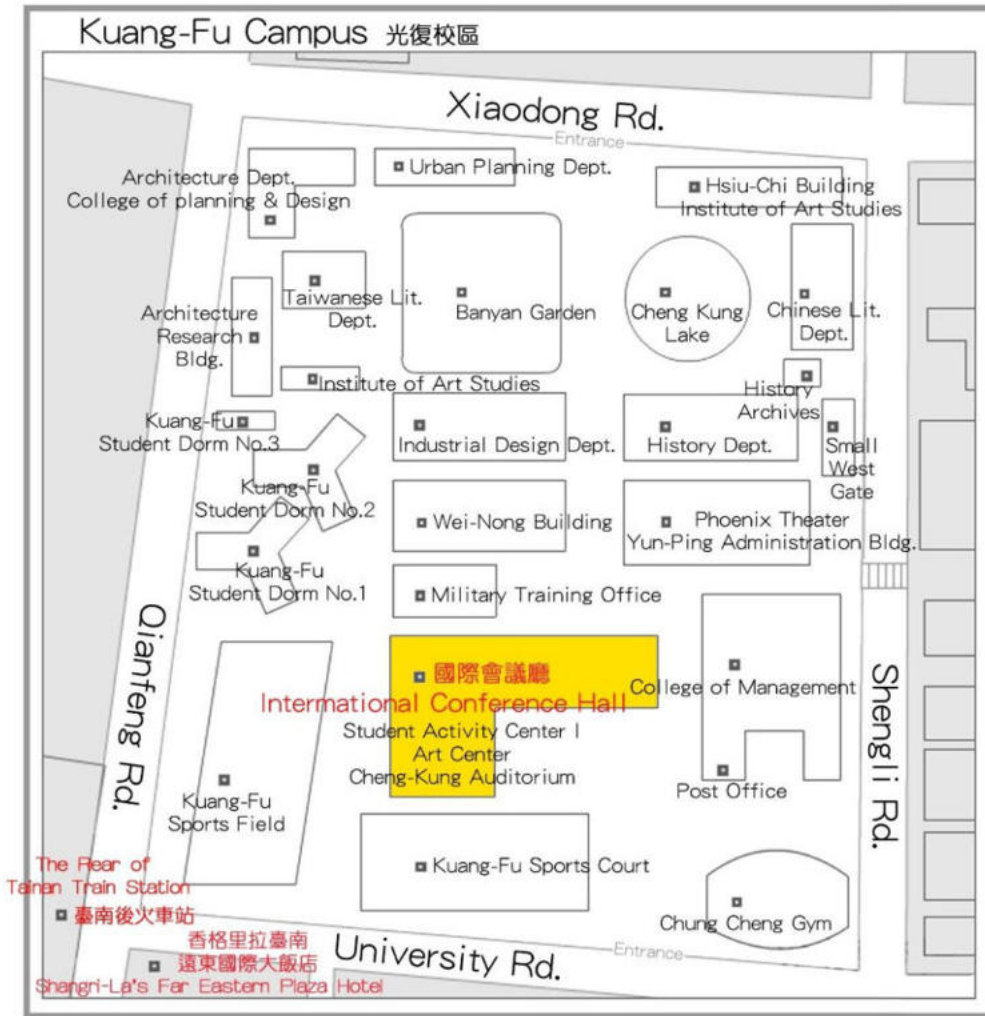


- 01 Aeronautical & Astronautical Eng. Dept.
- SL1 Alumni Association Center
- KF1 Architecture Dept.
- 02 Center for Micro/Nano Science & Technology
- CK14 Chemistry Dept.
- TzC2 Chemical Eng. Dept.
- KF7 Chinese Lit. Dept.
- CK8 Civil Eng. Dept.
- ChKuo2 College of Bioscience & Biotech.
- TzC7 College of Eng.
- TzC3 College of Eng. & Computer Science
- KF20 College of Management
- ChKuo3 College of Planning & Design
- CK12 College of Sciences
- LH5 College of Social Sciences
- KF3 College of Liberal Arts
- CK18 Computer Science & Info. Eng. Dept.
- CK15 Earth Sciences Dept.
- TzC3 Electrical Eng. Dept.
- CK21 Eng. Science Dept.
- CK6 Environmental Eng. Dept.
- CK17 Ge-Chi Hall
- CK11 Geomatics Dept.
- KF11 History Dept.
- CK3 Hydraulics & Ocean Eng. Dept.
- KF10 Industrial Design Dept.
- KF5 Institute of Art Studies
- CK2
- CK11 Materials Science & Eng. Dept.
- CK10 Mathematics Dept.
- TzC6 Mechanical Eng. Dept.
- LH1 Medicine & Nursing Dept.
- LH45 Mental Health Center
- CK1
- ChKuo1 Nursing Dept.
- ChKuo3 Occupational Therapy Dept.
- ChKuo3 Physical Therapy Dept.
- CK16 Physics Bldg. No.2
- CK13 Physics Dept.
- LH41 R&D Foundation
- CK14 Resources Eng. Dept.
- TzC7 Systems & Naval Mechatronic Eng. Dept.
- KF4
- ChKuo2 University Center for Bioscience & Biotech.
- KF2 Urban Planning Dept.
- KF5 Architecture Research Bldg.
- TzC4 Chi Mei Building
- CK7 Geotechnical Eng. Bldg.
- KF3 Hsu-Chi Building
- CK12 Info. Tech. Bldg.
- TzC5 Instrumentation Equipments Bldg.
- CK5 Main Library
- ChKuo2 Medical Lab. Science & Biotech. Bldg.
- CK19 Multi-Purpose Bldg.
- CK12 Physics & Chemistry Bldg.
- LH4 Public Health Bldg.
- 02 Science & Tech. Bldg.
- SL2 Students' Reading Hall
- LH2 The Uni. President Health Research Building
- KF15 Wei-Nong Building
- LH410 Institute of Archaeology
- ChKuo1 NCKU Hospital
- LH17 NCKU Hospital Bldg. No.2
- KF17 Military Training Office
- KF16 Yun-Ping Administration Bldg.
- KF19 Art Center
- ChKuo1 Cheng-Hsing Auditorium
- KF19 Cheng-Kung Auditorium
- CK13 Ge-Chi Auditorium
- KF9 History Archives
- KF18 International Conference Hall
- LH40 Magic School of Green Technology
- KF19 Student Activity Center I
- SL8 Student Activity Center II
- LH48 Taiwanese Lit. Dept.
- LH49 Life Sciences Dept.
- KF6 Banyan Garden
- KF8 Cheng Kung Lake
- CK20 NCKU Museum
- KF16 Phoenix Theater
- KF12 Small West Gate
- SL1 Zenda Suites
- KF23 Chung Cheng Gym
- KF22 Kuang-Fu Sports Court
- KF18 Kuang-Fu Sports Field
- SL3 Swimming Pool
- TzC1 Tzu-Chiang Sports Field
- 03 Aeronautical & Astronautical Eng. Dormitory
- CY4 Ching-Yeh Student Dorm No.1
- CY3 Ching-Yeh Student Dorm No.2
- CY2 Ching-Yeh Student Dorm No.3
- KF14 Kuang-Fu Student Dorm No.1
- KF13 Kuang-Fu Student Dorm No.2
- CY5 Medical Doctor Dormitory
- 05 Scholar Dormitory
- SL9 Sheng-Li Student Dorm No.1
- SL7 Sheng-Li Student Dorm No.2
- SL6 Sheng-Li Student Dorm No.3
- SL5 Sheng-Li Student Dorm No.5
- SL4 Sheng-Li Student Dorm No.6
- SL10 Sheng-Li Student Dorm No.8
- SL11 Sheng-Li Student Dorm No.9
- 04 Single Faculty Housing
- CY1 Single Faculty Housing
- CK9 Hsin Yuan
- CK20 Mail Room
- KF21 Post Office

- Centers & Dept.
- Buildings
- Hospital
- Administrations
- Auditorium
- Scenic Spots
- Sports
- Dorms & Lodgings
- Others

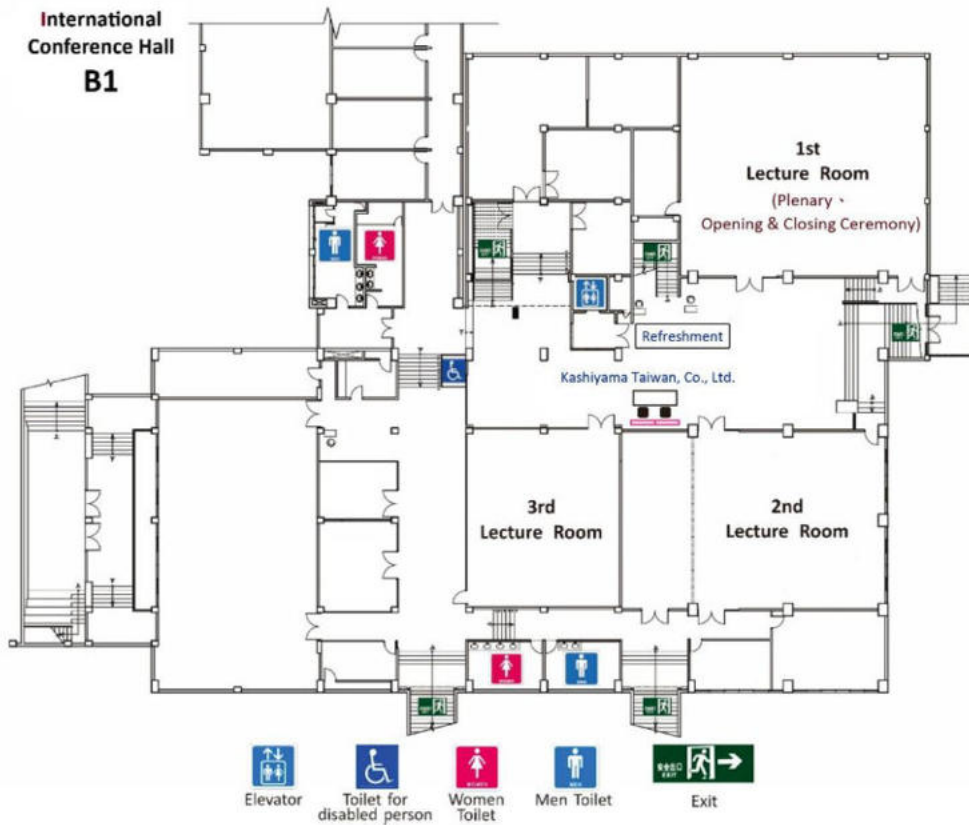
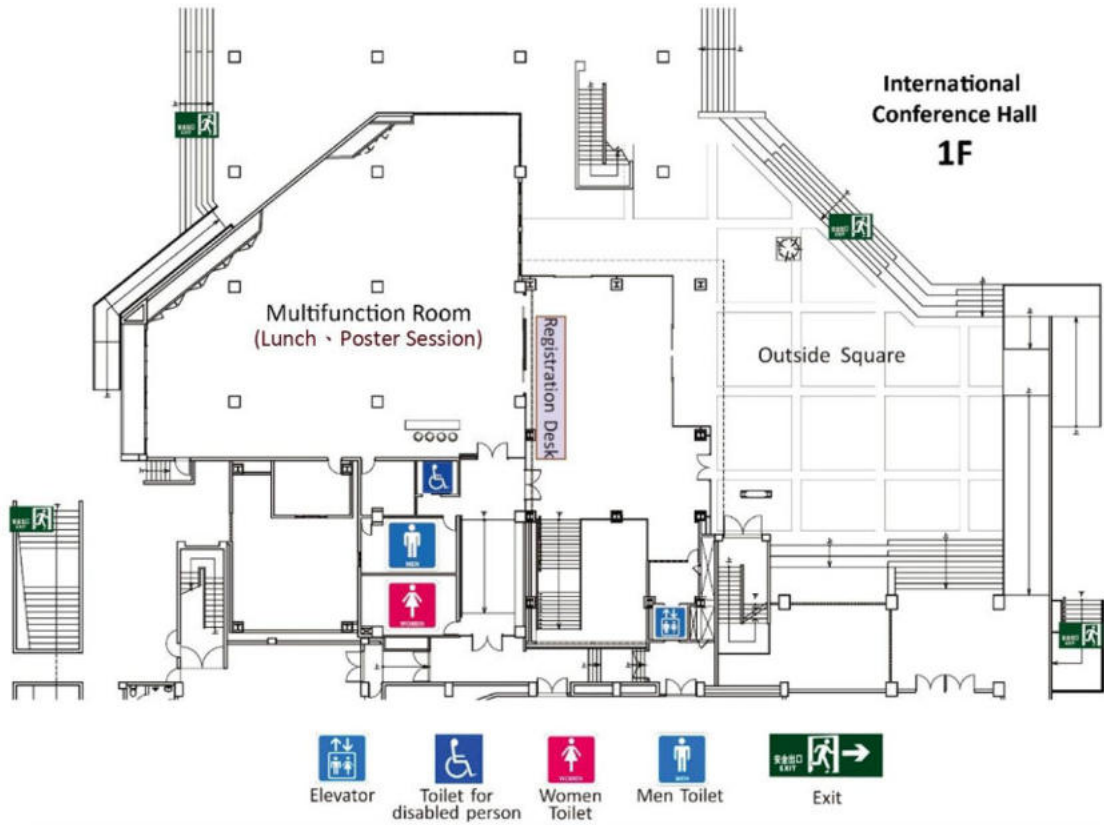


# ISGN-8 Map



# ISGN-8 Map

## International Conference Hall Floor Maps





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## Welcome

It is my great honor to welcome all distinguished participants and colleagues from around the world to the **8th International Symposium on Growth of III-Nitrides (ISGN-8)**, hosted at National Cheng Kung University in Tainan, Taiwan. As the Honorary Chair, I wish to express my sincere gratitude for your participation and support of this important event.

III-nitrides have become a cornerstone of modern science and technology. Their remarkable properties have enabled revolutionary advances in optoelectronics, high-power electronics, and emerging quantum devices. From high-efficiency LEDs to next-generation transistors, the impact of III-nitrides continues to transform industries and improve daily life worldwide.

The ISGN series has long provided a unique platform for sharing knowledge, fostering collaboration, and advancing this field. Each edition has showcased significant progress while strengthening ties among researchers and industry leaders. ISGN-8 proudly continues this mission, featuring a broad range of topics—from fundamental crystal growth to novel applications—reflecting the diversity and dynamism of III-nitride research.

As we gather in Tainan, a city known for its cultural heritage and academic vitality, I encourage participants to engage in open exchange, build collaborations, and inspire new ideas. The challenges ahead, such as developing more sustainable growth methods and exploring new device functionalities, require our collective creativity and commitment.

I would like to thank the organizing committee and all contributors for their tireless efforts in making this symposium possible. Their dedication ensures a meaningful and productive experience for all.

With great anticipation, I look forward to the stimulating discussions and achievements that will arise from ISGN-8. May this symposium inspire innovation, strengthen our global community, and create lasting collaborations and friendships.

A handwritten signature in black ink, reading "Yan-Kuin Su". The signature is fluid and cursive, with the first name "Yan" and last name "Su" clearly legible.

Prof. Yan-Kuin Su  
Honorary Chair, ISGN-8  
Academy of Innovative Semiconductor and Sustainable Manufacturing (AISSM)  
National Cheng Kung University, Taiwan  
November 10, 2025



## Welcome

On behalf of the Organizing Committee, it is my great honor and privilege to welcome you all to the 8th International Symposium on Growth of III-Nitrides (ISGN-8). After an unexpected hiatus caused by the global COVID-19 pandemic, it is truly heartening to see our community reunited again in 2025 to continue the proud tradition of this symposium.

Since its inception in 2006 in Linköping, Sweden, ISGN has served as a unique platform for scientists, engineers, and technologists from around the world to exchange the latest insights into the growth of III-nitride crystals, thin films, and nanostructures. Over the years, the symposium has traveled across Europe, Asia, and North America, reflecting the truly international spirit of our field.

This year's ISGN-8 provides an opportunity not only to showcase advances in bulk and epitaxial growth, characterization techniques, and nanostructure fabrication, but also to highlight the increasing importance of III-nitrides in next-generation high-power electronics and optoelectronic devices. By bringing together experts in crystal growth, materials science, and device applications, we aim to foster a deeper understanding of the fundamental science while paving the way for innovative technologies that can transform society.

I am confident that the discussions, presentations, and collaborations initiated here will enrich our collective knowledge and inspire new research directions. Equally important, ISGN-8 will provide a welcoming environment for young researchers and students, who represent the future of our field, to learn, interact, and build lasting professional connections.

I would like to take this opportunity to express my sincere gratitude to the International Advisory Committee (IAC), the Program Committee, our sponsors, and all the contributors who have made this symposium possible. Most importantly, I thank each of you for your participation and for bringing your expertise and enthusiasm to this meeting.

I warmly welcome you to ISGN-8 in Tainan, the ancient capital of Taiwan, and I look forward not only to stimulating scientific exchanges and fruitful collaborations, but also to the opportunity for you to experience the charm of this historic city. May this symposium be both intellectually rewarding and personally memorable for all of us.

With my very best wishes,

Prof. Ray-Hua Horng  
Conference Chair, ISGN-8  
Institute of Electronics (IEE)  
National Yang Ming Chiao Tung University, Taiwan  
November 10, 2025

# Committee

## Honorary Chair

Prof. Yan-Kuin Su	Chair Professor Emeritus, AISSM, National Cheng Kung University, Taiwan
國立成功大學 蘇炎坤 名譽講座教授	

## Conference Chair

Prof. Ray-Hua Horng	Chair Professor, IEE, National Yang Ming Chiao Tung University, Taiwan
國立陽明交通大學 洪瑞華 講座教授	

## General Program Chair

Prof. Wei-Chih Lai	Professor, DPs, National Cheng Kung University, Taiwan
國立成功大學 賴韋志 教授	

## General Program Committee Members

Prof. Cheng-Huang Kuo 郭政煌	National Yang Ming Chiao Tung University, Taiwan
Prof. Chia-Yen Huang 黃嘉彥	National Yang Ming Chiao Tung University, Taiwan
Dr. Chih-Wei Chu 朱治偉	Research Center for Applied Sciences, Academia Sinica, Taiwan
Prof. Chun-Kai Wang 王俊凱	National Kaohsiung University of Science and Technology, Taiwan
Prof. Hsiang-Chen Wang 王祥辰	National Chung Cheng University, Taiwan
Prof. Hsin-Chieh Yu 尤信介	National Yang Ming Chiao Tung University, Taiwan
Prof. Hsin-Ying Lee 李欣縈	National Cheng Kung University, Taiwan
Prof. Kung-Yen Lee 李坤彥	National Taiwan University, Taiwan
Prof. Ming-Chi Mitch Chou 周明奇	National Cheng Kung University, Taiwan
Prof. Sheng-Po Chang 張勝博	National Kaohsiung University of Science and Technology, Taiwan
Prof. Wu-Ching Chou 周武清	National Yang Ming Chiao Tung University, Taiwan
Prof. Ya-Ju Lee 李亞儒	National Cheng Kung University, Taiwan
Prof. Yu-Hsun Chou 周昱薰	National Cheng Kung University, Taiwan
Prof. Zhi-Ting Ye 葉志庭	National Chung Cheng University, Taiwan
<i>*The above committee member list is sorted in alphabetical order by name.</i>	

## International Advisory Committee Chair

Prof. Jen-Inn Chyi	Professor, National Central University, Taiwan
國立中央大學 蔡振瀛 教授	

## International Advisory Committee Members

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Dr. Andrew A. Allerman	Sandia National Laboratories, USA
Dr. Bernard Gil	CNRS, University of Montpellier, France
Prof. Bo Shen 沈波	Peking University, China
Prof. C. C. Yang 楊志忠	National Taiwan University, Taiwan
Prof. Debdeep Jena	Cornell University, USA
Prof. Euijoon Yoon	Seoul National University, South Korea
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Prof. Nicolas Grandjean	Ecole Polytechnique Fédérale de Lausanne (EPFL), Switzerland
Prof. Rachel Oliver	Cambridge University, UK
Prof. Russell Dupuis	Georgia Institute of Technology, USA
Dr. Sergey Ivanov	Ioffe Institute, Russia
Prof. Shoou-Jinn Chang 張守進	National Cheng Kung University, Taiwan
Prof. Yoichi Kawakami 川上 養一	Kyoto University, Japan
Prof. Zetian Mi	University of Michigan, USA
Prof. Zlatko Sitar	North Carolina State University, USA
<i>*The above committee member list is sorted in alphabetical order by name.</i>	

## Program Committee Chairs

Prof. Jinn-Kong Sheu	Distinguished Professor, DPs, National Cheng Kung University, Taiwan
國立成功大學 許進恭 特聘教授	
Prof. Yuh-Renn Wu	Professor, GIPO, National Taiwan University, Taiwan
國立臺灣大學 吳育任 教授	

## Program Committee Co-Chairs

Prof. Motoaki Iwaya 岩谷 素顯	Meijo University, Japan
Prof. Okhyun Nam	Tech University of Korea, South Korea
Prof. Shoou-Jinn Chang 張守進	National Cheng Kung University, Taiwan
Dr. Tim Wernicke	Technische Universität Berlin, Germany
Prof. Xin-Qiang Wang 王新強	Peking University, China

## Program Committee Members

Prof. Agata Kaminska	Polish Academy of Science, Poland
Dr. Andrew A. Allerman	Sandia National Laboratories, USA
Dr. Bernard Gil	CNRS, University of Montpellier, France
Prof. Chan-Shan Yang 楊承山	National Taiwan Normal University, Taiwan
Prof. Chao-Hsin Wu 吳肇欣	National Taiwan University, Taiwan
Prof. Che-Hao Liao 廖哲浩	National Yunlin University of Science and Technology, Taiwan
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Prof. Chia-Feng Lin 林佳鋒	National Chung Hsing University, Taiwan
Prof. Chia-Yen Huang 黃嘉彥	National Yang Ming Chiao Tung University, Taiwan
Prof. Chien-Chung Lin 林建中	National Taiwan University, Taiwan
Dr. Chih-Wei Chu 朱治偉	Research Center for Applied Sciences, Academia Sinica, Taiwan
Prof. Chun-Kai Wang 王俊凱	National Kaohsiung University of Science and Technology, Taiwan
Prof. Dong Seon Lee	Gwangju Institute of Science and Technology (GIST) , South Korea
Prof. Dong-Sing Wu 武東星	National Chi Nan University, Taiwan
Dr. Ekaterine Chikoidze	Université Paris-Saclay, France
Dr. Eva Monroy	CEA-Grenoble, France
Prof. Filip Tuomisto	University of Helsinki, Finland
Prof. Guo-En Chang 張國恩	National Chung Cheng University, Taiwan

Prof. Hao-Chung Kuo 郭浩中	National Yang Ming Chiao Tung University, Taiwan
Dr. Hideki Hirayama 平山 秀樹	RIKEN, Japan
Prof. Hsiang-Chen Wang 王祥辰	National Chung Cheng University, Taiwan
Prof. Hsin-Chieh Yu 尤信介	National Yang Ming Chiao Tung University, Taiwan
Prof. Hsin-Ying Lee 李欣縈	National Cheng Kung University, Taiwan
Dr. James R. Grandusky	Crystal IS, Inc., USA
Prof. Jian-Jang Huang 黃建璋	National Taiwan University, Taiwan
Prof. Juergen Christen	University of Magdeburg, Germany
Dr. Julien Brault	CRHEA, France
Prof. Ke-Jing Lee 李科靚	Cheng Shiu University, Taiwan
Prof. Kung-Yen Lee 李坤彥	National Taiwan University, Taiwan
Prof. Lung-Chien Chen 陳隆建	National Taipei University of Technology, Taiwan
Prof. Maki Kushimoto 久志本 真希	Nagoya University, Japan
Dr. Markus Weyers	FBH, Germany
Dr. Matthias Bickermann	Leibniz ICG, Germany
Prof. Meng-Chyi Wu 吳孟奇	National Tsing Hua University, Taiwan
Dr. Michał Boćkowski	Institute of High-Pressure Physics, Polish Academy of Sciences, Poland
Prof. Ming-Chi Mitch Chou 周明奇	National Cheng Kung University, Taiwan
Prof. Sheng-Po Chang 張勝博	National Kaohsiung University of Science and Technology, Taiwan
Prof. Shigefusa Chichibu 秩父 重英	Tohoku University, Japan
Prof. Shyh-Jer Huang 黃士哲	National Formosa University, Taiwan
Dr. Stefan Schulz	Photonics Theory Group, Tyndall National Institute, Ireland
Prof. Sung Kyun Park	Pusan National University, South Korea
Prof. Tae-Yeon Seong	Korea University, South Korea
Prof. Takashi Matsuoka 松岡 隆志	Tohoku University, Japan
Prof. Tetsuya Takeuchi 竹内 哲也	Meijo University, Japan
Prof. Tian-Li Wu 吳添立	National Yang Ming Chiao Tung University, Taiwan
Prof. Wu-Ching Chou 周武清	National Yang Ming Chiao Tung University, Taiwan
Prof. Ya-Ju Lee 李亞儒	National Cheng Kung University, Taiwan
Prof. Yoichi Kawakami 川上 養一	Kyoto University, Japan
Prof. Young Joon Hong	SungKyunKwan University, South Korea
Prof. Yu-Hsun Chou 周昱薰	National Cheng Kung University, Taiwan
Dr. Yun-Chong Chang 張允崇	Research Center for Applied Sciences, Academia Sinica, Taiwan

Prof. Zetian Mi	University of Michigan, USA
Prof. Zhi-Ting Ye 葉志庭	National Chung Cheng University, Taiwan
Dr. Zi-Hao Wang 王子豪	National Cheng Kung University, Taiwan
<i>*The above committee member list is sorted in alphabetical order by name.</i>	

## Topic Chair & Co-Chair

### S1. III-N Bulk Crystal Growth

Chair	Prof. Ming-Chi Mitch Chou 周明奇	National Cheng Kung University, Taiwan
Co-Chair	Dr. James R. Grandusky	Crystal IS, Inc., USA

### S2. III-N Epitaxial Growth Techniques

Chair	Prof. Cheng-Huang Kuo 郭政煌	National Yang Ming Chiao Tung University, Taiwan
Co-Chair	Dr. Julien Brault	CRHEA, France

### S3. III-N Ternary and Quaternary Alloys

Chair	Prof. Chia-Yen Huang 黃嘉彥	National Yang Ming Chiao Tung University, Taiwan
Co-Chair	Dr. Hideki Hirayama 平山 秀樹	RIKEN, Japan

### S4. III-N Nanostructures and 2D Materials

Chair	Prof. Yu-Hsun Chou 周昱薰	National Cheng Kung University, Taiwan
Co-Chair	Prof. Zetian Mi	University of Michigan, USA

### S5. III-N Heterostructure Characterization

Chair	Prof. Chan-Shan Yang 楊承山	National Taiwan Normal University, Taiwan
Co-Chair	Dr. Andrew A. Allerman	Sandia National Laboratories, USA

### S6. III-N Defect Control and Surface Effects

Chair	Prof. Hsiang-Chen Wang 王祥辰	National Chung Cheng University, Taiwan
Co-Chair	Prof. Che-Hao Liao 廖哲浩	National Yunlin University of Science and Technology, Taiwan

### S7. III-N Optical and Electrical Properties

Chair	Prof. Chien-Chung Lin 林建中	National Taiwan University, Taiwan
Co-Chair	Prof. Hsin-Chieh Yu 尤信介	National Yang Ming Chiao Tung University, Taiwan

### S8. III-N Device Modeling and Simulation

Chair	Prof. Ya-Ju Lee 李亞儒	National Cheng Kung University, Taiwan
Co-Chair	Dr. Stefan Schulz	Photonics Theory Group, Tyndall National Institute, Ireland

### S9. III-N Spin-related Phenomena

Chair	Dr. Yun-Chorng Chang 張允崇	Research Center for Applied Sciences, Academia Sinica, Taiwan
Co-Chair	Dr. Bernard Gil	CNRS, UNiversity of Montpellier, France

### S10. III-N Devices—FETs, LEDs, and Lasers

Chair	Prof. Zhi-Ting Ye 葉志庭	National Chung Cheng University, Taiwan
Co-Chair	Prof. Maki Kushimoto 久志本 真希	Nagoya University, Japan

### Special Session. Ultrawide-bandgap materials and devices

Chair	Prof. Hsin-Ying Lee 李欣縈	National Cheng Kung University, Taiwan
Co-Chair	Dr. Ekaterine Chikoidze	Université Paris-Saclay, France

# General Information

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## About ISGN-8

The 8th International Symposium on Growth of III-Nitrides (ISGN-8) is hosted by:

- National Cheng Kung University, Taiwan
- Department of Photonics, National Cheng Kung University, Taiwan
- Institute of Electronics, National Yang Ming Chiao Tung University, Taiwan
- Graduate Institute of Photonics and Optoelectronics, National Taiwan University, Taiwan
- National Science and Technology Council, Taiwan

and technically co-sponsored by:

- Academy of Innovative Semiconductor and Sustainable Manufacturing, National Cheng Kung University, Taiwan
- Taiwan Vacuum Society, Taiwan
- Ministry of Education, Taiwan
- Center of Crystal Research, Taiwan
- IEEE Photonics Society, Taiwan

## Venue

International Conference Hall, Kuang-Fu Campus  
National Cheng Kung University (NCKU), Tainan, Taiwan  
國立成功大學 光復校區 國際會議廳  
*No.1, University Road, Tainan City 701, Taiwan*

## Official Language

The official language of ISGN-8 is English.

## Registration

The ISGN-8 registration counter is located in the 1F, International Conference Hall.

Registration hours	
November 10, 2025 (Monday)	08:30 to 17:00
November 11, 2025 (Tuesday)	08:00 to 17:00
November 12, 2025 (Wednesday)	08:00 to 09:15

ISGN-8 registration includes admission to all ISGN-8 sessions, plenaries, panels, poster sessions, exhibitions, coffee breaks, lunches, and the banquet. Upon registration, you will receive your ISGN-8 materials, including an ISGN-8 bag, an identification badge, and an advanced program. The identification badge must be worn at all ISGN-8 activities.

## Lunch Break

During the ISGN-8 (Nov. 10 - Nov. 12), we will provide lunch for the participants. Please remember to bring your identification badge when picking up your lunch. After collecting your meal, you can enjoy it in the following conference rooms and dining areas:

November 10, 2025 (Monday)	Multifunction Room(1F), International Conference Hall
November 11, 2025 (Tuesday)	
November 12, 2025 (Wednesday)	Bread box (takeaway available)

## ISGN-8 Banquet

Date: November 11, 2025 (Tuesday)

Time: 18:00-20:30

Venue: B2F, Far Eastern Grand Ballroom, Shangri-La's Far Eastern, Tainan

台南遠東香格里拉 B2F 遠東宴會廳

No. 89, Section West, University Rd., East Dist., Tainan City 701, Taiwan



## Coffee Break

The coffee breaks will be held in the Venue of ISGN-8 (International Conference Hall):

November 10, 2025 (Monday)	10:10 to 10:20
	14:45 to 15:00
November 11, 2025 (Tuesday)	10:10 to 10:20
	14:45 to 15:00
November 12, 2025 (Wednesday)	09:15 to 11:00

## Exhibitions

The exhibition will be held on the B1F of the International Conference Hall. The Exhibition will offer the opportunity to search for the latest products, technology, and services. Attendees are encouraged to visit the displays during the ISGN-8.

## Access to the Internet

Free internet access is provided in the Venue of ISGN-8 for the convenience of the participants.

Wi-Fi SSID: 2025ISGN8

Password: wifi1112



## ISGN-8 Secretariat (NCKU)

*Mr. H. W. Chen*

*Department of Photonics, National Cheng Kung University (NCKU)*

*No.1, University Road, Tainan City 701, Taiwan*

*E-mail: [isgn8@ncku.edu.tw](mailto:isgn8@ncku.edu.tw)*

# Presentation Information

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## Presentation timeslot

Session type	Plenary	Invited	Oral
Total length	50 mins (including 5 mins Q&A)	30 mins (including 3 mins Q&A)	15 mins (including 3 mins Q&A)

## Before the presentation

- Please arrive at the session meeting rooms 15 minutes earlier and reconfirm your presentation slides with conference staff.
- Conference staff will stay in the meeting rooms to provide relevant assistance accordingly.
- **All presentations should be presented in English.**
- For an oral presenter, we will allocate 12 minutes for the lecture plus 3 minutes for discussion. In every lecture, we will hold up a sign at the 11th minute to remind you that you have one more minute to enter the Q&A session. At the 12th minute, we will remind you to start the Q&A, at the 15th minute, we will remind you that time is up.

## Facilities in the session rooms

- In each session room, there will be a computer and a projector. **The projectors in all the classrooms are 4:3.** The operating system of the computer is **Microsoft Windows 11.**
- In each session, the computer will be equipped with USB ports to read a USB flash drive. The presenter must load the presentation file onto the session room computer before the beginning of the session.
- In general, it is not suggested to connect your own computer to the projector in the session room.

## Instructions for Poster Presentation

- Poster presentations will be held in the Multifunction Room (1F).
- Presenters should arrive 15 minutes earlier to set up their posters.
- **The poster size is 90 cm (W) x120 cm (H).**
- Presenters are not required to upload their posters in advance. Kindly bring your poster with you and display it on-site on the day of your scheduled presentation.
- Presenters must be around their bulletin boards to make their presentations and answer questions during the poster sessions.
- Presenters who wish to keep their posters should remove them after the presentation.
- Any remaining posters will be removed by conference staff when the session ends.

Session	Time	Set Up
Poster Session	15:00-17:00, Tuesday, November 11, 2025	15 mins earlier

# Iwińska Award

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## Iwińska Award – In Memory of Dr. Małgorzata Iwińska (1985–2024)

The ISGN-8 proudly introduces the Iwińska Award, established to honor the memory and legacy of Dr. Małgorzata Iwińska, a brilliant researcher, inspiring mentor, and valued member of the nitride semiconductor community.

Dr. Iwińska passed away in 2024, leaving behind a legacy of outstanding scientific contributions in the field of gallium nitride (GaN) crystal growth. In recognition of her impact, the Iwińska Award will be presented for the Best Student Presentations at ISGN-8.

## About Dr. Małgorzata Iwińska – Scientific Biography

- Graduate of the Physics Departments of Warsaw University and Warsaw University of Technology
- Since 2014, researcher at the Crystal Growth Laboratory, Institute of High Pressure Physics (Unipress), Polish Academy of Sciences
- 2015: Winner of the Yamaguchi Masahito Award at LEDIA 2015 for *“HVPE-GaN Growth on GaN-based Advanced Substrate by Smart Cut™”*
- 2019: PhD with distinction – *“HVPE as a Method for Crystallizing GaN with Low Background Impurity Concentration with Controllable Doping – Highly Conductive n-type and Semi-insulating Material”*
- Visiting Associate Professor at the New Industry Creation Hatchery Center, Tohoku University, Japan
- Coordinator and scientific lead at Unipress for multiple international projects, including *“GaN for Advanced Power Applications”* under the 2020 ECSEL IA Call
- Author of 52 scientific publications, cited nearly 1,000 times

Beyond her scientific excellence, Dr. Iwińska was admired for her collegial spirit, kindness, and support for young researchers around the world.

## About the Award

- Name: Iwińska Award – Best Student Presentation
- Eligibility: Only **student** presenters (oral) in *S1. III-N Bulk Crystal Growth* and *S5. III-N Heterostructure Characterization* are eligible for the award
- Form of Award: Certificate and prize
- Number of Recipients: One
- Sponsor: Institute of High Pressure Physics (Unipress), Polish Academy of Sciences

To be eligible for the awards, you must meet the following criteria:

1. The student has to register to attend the conference in person.
2. The student should be the presenter of the paper and present it in English.
3. All awardees must present a valid identification document (ID card, Passport, or ARC) and an official proof of student status (e.g., Student ID card) for identity verification and award collection.

This award serves not only to commemorate Dr. Iwińska's achievements but also to support and inspire emerging talents in the field of III-nitrides.

### List of Candidates for the Iwińska Award

Day 1-11/10 (Monday) @ 2nd Lecture Room			
Manuscript ID	Time	Presenter	Title
0107	13:30-13:45	Krzysztof Gołyga	Novel GaN Seed Architecture for Bulk Crystal Growth Processes Based on Surface Bonding
0064	13:45-14:00	Naoki Fujimoto	Correlation between reactor polycrystal amount and large pit formation in GaN growth by oxide vapor phase epitaxy
0065	14:00-14:15	Kosei Asao	Dependence of thermal conductivity on oxygen concentration in GaN grown by OVPE method
0081	15:00-15:15	Shogo Washida	<i>Surface Planarization and Reduction of Threading Dislocation Density of GaN Crystals after Facet Growth in the Na-flux Method</i>
0048	16:30-16:45	Jeong Kyun OH	<i>Enhanced Green Hydrogen Generation Using GO-GaN Photoanodes in Direct Seawater Splitting</i>
0104	16:45-17:00	Pham Tu Huynh	<i>Defects Visualization in GaN-based HEMTs with SiNx nano-mask by Cathodoluminescence Spectroscopy</i>
Reviewers			
Prof. Filip Tuomisto (University of Helsinki, Finland)			
Dr. Michał Boćkowski (Institute of High-Pressure Physics, Polish Academy of Sciences, Poland)			
Prof. Ray-Hua Horng (National Yang Ming Chiao Tung University, Taiwan)			
Prof. Takashi Matsuoka (Tohoku University, Japan)			
Prof. Wei-Chih Lai (National Cheng Kung University, Taiwan)			
Prof. Yuh-Renn Wu (National Taiwan University, Taiwan)			

# ISGN-8 Speakers

## Plenary Speakers

### *Day 1-November 10 (Monday)*

Time	Room	Speaker	Title
09:20-10:10	1st Lecture Room, B1F	<b>Prof. Zetian Mi</b> University of Michigan, USA	<i>Ferroelectric Nitride Semiconductors: Epitaxy, Properties, and Emerging Device Applications</i>
10:20-11:10		<b>Prof. Kei May Lau 劉紀美</b> The Hong Kong University of Science and Technology, Hong Kong	<i>Growth of Vertical GaN Power Devices on Foreign and Native Substrates</i>
11:10-12:00		<b>Prof. Elison Matioli</b> Ecole Polytechnique Fédérale de Lausanne (EPFL), Switzerland	<i>Emerging technologies for high-performance GaN power devices</i>

### *Day 2-November 11 (Tuesday)*

Time	Room	Speaker	Title
08:30-09:20	1st Lecture Room, B1F	<b>Prof. Jen-Inn Chyi 蔡振瀛</b> National Central University, Taiwan	<i>Growth of h-BN and Its Mediated Growth of III-Nitrides on Foreign Substrates by van der Waals Epitaxy</i>
09:20-10:10		<b>Dr. Hideki Hirayama 平山 秀樹</b> RIKEN, Japan	<i>Recent progress of Far-UVC LEDs fabricated on C-sapphire and their applications</i>
10:20-11:10		<b>Prof. James S. Speck</b> University of California, Santa Barbara, USA	<i>V-defect Science and Engineering for High Efficiency LEDs</i>
11:10-12:00		<b>Prof. Debdeep Jena</b> Cornell University, USA	<i>Homoepitaxial growth on bulk AlN for ultrawide bandgap electronics and photonics</i>

*Day 3-November 12 (Wednesday)*

Time	Room	Speaker	Title
08:25-09:15	1st Lecture Room, B1F	<b>Prof. Xiuling Li</b> University of Texas, USA	<i>Ferroelectric Nitrides by MOCVD: Challenges and Opportunities</i>



# ISGN-8 Plenary Session

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## Plenary Session 1



**Prof. Zetian Mi**

Professor, University of Michigan, USA

**AM 09:20-10:10, November 10, 2025**

**1st Lecture Room**

Presider: Prof. Ray-Hua Horng

<b>Title</b>
<i>Ferroelectric Nitride Semiconductors: Epitaxy, Properties, and Emerging Device Applications</i>
<b>Abstract</b>
<p>The incorporation of group IIIB elements, e.g., Sc and Y, can transform conventional III-nitride semiconductors to be ferroelectric, with significantly enhanced piezoelectric, dielectric, and linear and nonlinear optical properties. In this talk, I will discuss the underlying physics and mechanisms of significantly enhanced piezoelectric response, ferroelectric switching, domain wall kinetics, and polarization dynamics. I will then present the recent advances of molecular beam epitaxy and characterization of ferroelectric nitride heterostructures and nanostructures. Their emerging applications in high electron mobility transistors, memory and acoustic devices, as well as integrated photonics, together with the obstacles faced by nitride ferroelectrics will be presented.</p>

## Plenary Session 2



**Prof. Kei May Lau**  
劉紀美

Professor Emeritus, The Hong Kong University of Science and Technology, Hong Kong

**AM 10:20-11:10, November 10, 2025**

**1st Lecture Room**

Presider: Prof. Ray-Hua Horng

Title
<i>Growth of Vertical GaN Power Devices on Foreign and Native Substrates</i>
Abstract
<p>Vertical GaN-based power devices have tremendous potential in achieving high power handling capabilities and power delivery density compared with lateral GaN HEMTs [1]. Two terminal PIN diodes and trench MOSFETs stand out as simple choices that can offer switching and intrinsic normally-off operation with a p-GaN inversion channel, providing a high positive threshold voltage to prevent false turn-on. The p-n junction for OFF-state blocking can provide avalanche capability, which is vital for high power applications. Furthermore, a relatively simple fabrication process requiring no regrowth has been demonstrated.</p> <p>Quasi-vertical GaN trench MOSFETs can be grown on cost-effective foreign substrates, such as sapphire and silicon[2]. For fully-vertical devices with drain contact at the substrate backside, GaN-on-silicon trench MOSFETs have been materialized using a complicated substrate removal process.</p> <p>Alternatively, trench MOSFETs on a conductive buffer grown on doped substrates would greatly simplify the fabrication process. SiC has been shown to be the most sensible choice to realize high-performance fully-vertical GaN-on-SiC diodes with a conductive AlGaN buffer. In addition</p>

to the advantage of smaller mismatch between GaN and SiC, the high thermal conductivity of SiC substrates is highly desirable for power applications. It's also possible to integrate GaN and SiC devices to combine their advantages if a GaN-on-SiC platform is used [3]. Recently, quasi-vertical GaN-on-SiC FinFETs are demonstrated. The challenge of growing trench VMOS on SiC is optimization of the conductive buffer to grow a thick drift layer. The other option is using highly doped native GaN substrates.

We will discuss the growth of GaN-based diodes and trench MOS on all the different substrates to balance all the trade-offs of the on- and off-state characteristics of the devices. For the OFF-state, electric field crowding at trench corners can lead to premature breakdown. We also developed a trench etching process and application of a thick bottom dielectric (TBD) in fully-vertical GaN-on-GaN trench MOSFETs, which mitigates this electric field crowding and successfully increases the breakdown voltage (VBR)<sub>T</sub>.

#### REFERENCES:

- [1] Andrew T. Binder et al., *Appl. Phys. Express*, 17, 101003, 2024.
- [2] R. Zhu et al., *IEEE Electron Device Lett.*, 43, 346-349, 2022.
- [3] J. Li et al., *IEEE Electron Device Lett.*, 46, 282-285, 2025.

## Plenary Session 3



**Prof. Elisa Matioli**

Professor, Ecole Polytechnique Fédérale de Lausanne (EPFL), Switzerland

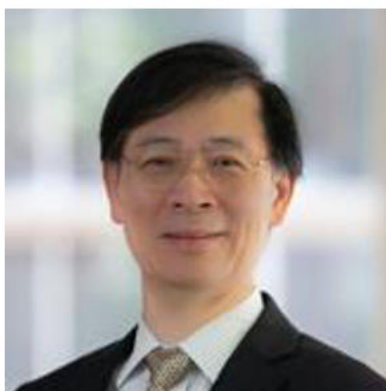
**AM 11:10-12:00, November 10, 2025**

**1st Lecture Room**

Presider: Prof. Ray-Hua Horng

<b>Title</b>
<i>Emerging technologies for high-performance GaN power devices</i>
<b>Abstract</b>
<p>This presentation will discuss recent advancements and emerging technologies based on III-Nitride semiconductors that aim to address some of the main challenges in power electronics. We will highlight the significant improvements in device performance achieved through the use of multi-channel structures, resulting in figures of merit that far exceed current state of the art. To address the challenge of managing high heat fluxes in compact devices, we will explore recent advancements in the thermal management of GaN devices. This includes the co-design of microfluidics and electronics within the same semiconductor substrate, a technology that offers significantly greater cooling capabilities than currently available and enables denser integration of GaN devices on a single chip. These emerging technologies present exciting opportunities for the future development of III-nitride electronic devices.</p>

## Plenary Session 4



**Prof. Jen-Inn Chyi**  
**蔡振瀛**

Vice President & Professor, National Central University, Taiwan

**AM 08:30-09:20, November 11, 2025**

**1st Lecture Room**

Presider: Prof. Yuh-Renn Wu

Title
<p data-bbox="225 1126 1366 1227"><i>Growth of h-BN and Its Mediated Growth of III-Nitrides on Foreign Substrates by van der Waals Epitaxy</i></p>
Abstract
<p data-bbox="204 1323 1386 1597">Hexagonal boron nitride (h-BN) is a wide-bandgap III-V two-dimensional semiconductor known for its exceptional thermal conductivity, high-temperature stability, and strong chemical inertness. These unique properties have sparked growing interest in its use across a range of emerging applications, including active layers for UV optoelectronics, insulators for 2D electronics, single-photon emitters for quantum computing, tunneling spin valves for spintronics, and ferroelectric transistors for next-generation memory devices.</p> <p data-bbox="204 1659 1386 1977">However, the commercialization of h-BN-based technologies has been hindered by challenges in synthesizing large, single-crystalline bulk crystals or producing uniform thin films over large areas in an affordable way. Although material growth techniques for h-BN continue to advance, new challenges and opportunities are arising in parallel. To date, various substrates have been employed for h-BN film growth, such as sapphire, nickel, copper, platinum, silicon, and diamond. Each substrate presents its own advantages and drawbacks in terms of film quality and cost-effectiveness for commercial-scale production.</p>

III-nitride semiconductor epilayers are typically grown on single-crystalline foreign substrates, which often compromise material quality due to lattice mismatch, incompatible crystal symmetry, and limited thermal stability. These issues significantly constrain the development of application-specific epitaxial structures. Recent research has demonstrated that using h-BN as an intermediate layer enables van der Waals epitaxy of III-nitrides on polycrystalline AlN substrates, (100) silicon, and amorphous SiO<sub>2</sub>. As a proof of concept, a multiple-quantum-well (MQW) heterostructure was successfully fabricated on an h-BN-coated poly-AlN substrate, emitting light at a wavelength of 423 nm. This achievement highlights the potential of h-BN for flexible GaN-based light-emitting diodes and opens new avenues for III-nitride device integration on thermally robust substrates, while mitigating crystallographic constraints.

## Plenary Session 5



**Dr. Hideki Hirayama**  
平山 秀樹

Chief Scientist, RIKEN, Japan

AM 09:20-10:10, November 11, 2025

1st Lecture Room

Presider: Prof. Yuh-Renn Wu

Title
<i>Recent progress of Far-UVC LEDs fabricated on C-sapphire and their applications</i>
Abstract
<p>Human harmless short wavelength 230 nm AlGaIn far-UVC LED fabricated on sapphire substrate is promising for potential applications of any kind of virus inactivation used in the spaces where people are present. Up to now, the light power of the 230 nm far-UVC LED is lower than those of 265-280 nm LEDs. We demonstrated efficiency increase in 220-230 nm far-UVC LEDs fabricating on AlN/c-sapphire by improving internal quantum efficiency (IQE), injection efficiency (IE), and light-extraction efficiency (LEE).</p> <p>We have demonstrated 0.8-1.5% EQE for 232-236 nm LEDs by introducing polarization doping (PD) layer for transparent p-contact layer. We also challenged short wavelength 219-222 nm LEDs by introducing PD hole injection layer. We also demonstrated efficiency increase by about 4 times in 232 nm LED by introducing photonic crystal (PhC) reflector on p-AlGaIn/p-GaN contact layer and obtain single more than 10 mW light power. 80 chips of 230 nm LED with 2.7 mW pulse operation power were integrated to copper heat sink and we demonstrated 220 mW power far-UVC light module. The 230 nm far-UVC power LED module fabricated on sapphire can be provided in low cost and would be available for virus inactivation applications in human-working space.</p>

## Plenary Session 6



**Prof. James S. Speck**

Seoul Viosys Distinguished Professor, University of California, Santa Barbara, USA

**AM 10:20-11:10, November 11, 2025**

**1st Lecture Room**

President: Prof. Yuh-Renn Wu

Title
<i>V-defect Science and Engineering for High Efficiency LEDs</i>
Abstract
<p>In this presentation we provide an overview of the early history of V-defects in visible LEDs. We then consider vertical transport in long wavelength LEDs without V-defects and the significant polarization and bandoff barrier at high indium content InGaN QWs. Then we show key work on the benefits of V-defects for low voltage operation via lateral injection through V-defect sidewalls. We show the latest understanding of the structure of V-defects including the observation of the threading dislocation on the V-defect sidewalls. We demonstrate a new method for generating new threading dislocations with controlled density that are subsequently used to control V-defect density. We presentation experimental evidence for lateral injection via: direct electron emission microscopy experiments; scanning near field optical microscopy studies; and scanning tunneling luminescence studies. We demonstrate atomic layer etching of p-GaN to faithfully reveal buried V-defects. We present recent results in 2D and 3D simulations of lateral electron and hole injection through the V-defect sidewalls to the planar emitting QWs.</p>

## Plenary Session 7



**Prof. Debdeep Jena**

David E. Burr Professor of Engineering, Cornell University, USA

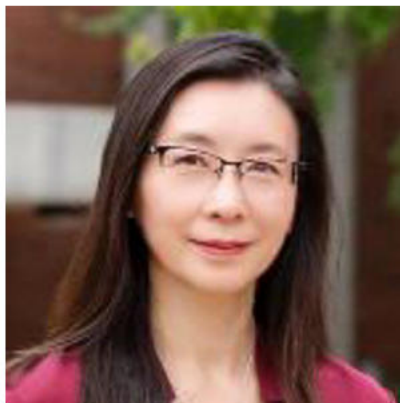
**AM 11:10-12:00, November 11, 2025**

**1st Lecture Room**

President: Prof. Yuh-Renn Wu

Title
<i>Homoepitaxial growth on bulk AlN for ultrawide bandgap electronics and photonics</i>
Abstract
The availability of bulk AlN substrates has rejuvenated our field on nitride semiconductors. In this presentation, I will cover recent results on epitaxial growth on bulk AlN substrates, the challenges encountered, and new findings in growth and subsequent epitaxial layers. I will cover the growth of sharp and graded heterostructures, and their structural, electronic, and optical properties and uses in electronic and photonic devices.

## Plenary Session 8



**Prof. Xiuling Li**

Temple Foundation Endowed Professorship No. 3 Professor, University of Texas, USA

**AM 08:25-09:15, November 12, 2025**

**1st Lecture Room**

Presider: Prof. Wei-Chih Lai

<b>Title</b>
<i>Ferroelectric Nitrides by MOCVD: Challenges and Opportunities</i>
<b>Abstract</b>
Ferro-nitrides such as AlScN and AlBN are promising for non-volatile memory and RF devices, including applications in extreme environments. Scaling these materials by MOCVD is attractive but challenging, as Sc and B precursors exhibit extremely low vapor pressures, limiting delivery and incorporation. Using a close-coupled showerhead reactor, we investigate the growth of AlScN and AlBN, examining how growth temperature, pressure, rate, template morphology, and crystallinity influence Sc incorporation and ferroelectric behavior. Ferroelectric switching, temperature dependence, and endurance are presented, highlighting both the opportunities and remaining challenges for MOCVD of ferro-nitrides.

# ISGN-8 Speakers

## Invited Speakers

*Day 1-November 10 (Monday)*

S1. III-N Bulk Crystal Growth		
@2nd Lecture Room, B1F		
Time	Speaker	Title
13:00~13:30	Dr. Michał Boćkowski Institute of High-Pressure Physics, Polish Academy of Sciences, Poland	<i>The Science and Art of GaN Crystal Growth</i>
Abstract	Gallium nitride (GaN) is central to modern optoelectronics and high-power electronics, but further progress depends on advances in crystal growth. This lecture reviews recent developments in bulk GaN crystallization, with emphasis on the basic ammonothermal method and its integration with halide vapor phase epitaxy (HVPE). Key challenges—including scalability, reactor design, and seed preparation—will be examined alongside issues in wafer processing and surface treatment. Particular focus will be given to hybrid growth strategies that combine the strengths of different techniques. Finally, future milestones toward large-diameter GaN substrates will be outlined, enabling next-generation lasers, transistors, and high-performance power devices.	
S4. III-N Nanostructures and 2D Materials		
@3rd Lecture Room, B1F		
Time	Speaker	Title
13:30-14:00	Dr. Bernard Gil CNRS, University of Montpellier, France	<i>The Optical Properties of Various Polytypes of sp<sup>2</sup>-bonded Boron Nitride.</i>
Abstract	Hexagonal boron nitride (h-BN), an insulating two-dimensional layered material, has attracted great attention due to its fascinating properties and promising applications across the fields of photonics, quantum optics, and electronics. Given the layered structure of h-BN, various polytypes exist with high-symmetry stacking sequences where successive layers are rotated or translated, leading to a variety of physical properties. Similarly to silicon carbide, polytypism in sp <sup>2</sup> -bonded boron nitride is to lead to a wealth of variations in the optoelectronic properties. I will report on the optical properties of a variety BN polytypes including bulk crystals grown by precipitation out of molten metallic solutions and epilayers by	

produced by metal-organic chemical vapor deposition on sapphire substrates [1,2]. The sp<sup>2</sup>-bonded layered compound BN exists in more than a handful of different polytypes (i.e. different layer stacking sequences) with similar formation energies, which makes obtaining a pure monotype single crystals extremely tricky. Co-existence of polytypes in a similar crystal leads to formation of many interfaces and structural defects having deleterious influence on the internal quantum efficiency of the light- emission and on the mobility of carriers. Light emission, when recorded in standard experimental illumination conditions, is in general inhomogeneous and its yield is dominated to radiative recombination to localized stacking faults [3], even for crystals with state-of-the- art, high structural quality [4]. However, despite of this, lasing operation was reported at 215 nm [5], which has shifted the interest of sp<sup>2</sup>-bonded BN from the laboratories of basic sciences to the fields of optoelectronic and electrical device applications. Here I present X-ray diffraction, electron microscopy and Raman light scattering experiments that were performed on a large variety of samples grown using the complementary techniques alluded to above and that we interpret with the help of group theory arguments and calculations of the phonon dispersion relations (in the context of quantum espresso). They revealed the three coherently ordered AA' (normal), AB (Bernal), and ABC or rBN (Rhombohedral) and AA stackings, and the disordered turbostratic (tBN) one. Characterization of the different structural polytypes are completed by micro-photoluminescence experiment measurements that furnish a one-by-one, unambiguous relationship between the sp<sup>2</sup>-stacking and its photoluminescence spectrum [6,7,8,9]. These, together with reflectance experiment disentangle the nature of the light-matter interaction processes in sp<sup>2</sup>-bonded BN. All polytypes studied here display an indirect configuration of their fundamental bandgap, some of them (the AA and AB two-layer stackings and the rBN three-layer one) offer efficient Second Harmonic Generation of light performances.

#### References:

- [1] Jiahan Li et al. ACS Nano 15, 7032 (2021).
- [2] M. Chubarov et al., Crystal Growth Design 12, 3215 (2012)
- [3] R. Bourrellier et al. ACS Photonics 1, 857 (2014).
- [4] G. Cassabois et al. Nature Photonics 10, 262, (2016).
- [5] K. Watanabe et al. Nature Materials 3, 404 (2004).
- [6] M. Rousseau et al. Physical Review Materials 5, 064602 (2021).
- [7] M. Moret et al. Applied Physics Letters 119, 262102 (2021).
- [8] S.Moon et al. Nature Materials (2025) DOI10.1038/s41563-025-02173-2
- [9] W.Desrat et al submitted to Physical Review Materials (under review)

S5. III-N Heterostructure Characterization		
@2nd Lecture Room, B1F		
Time	Speaker	Title
15:30-16:00	<b>Prof. Frank Bertram</b> Otto-von-Guericke-University Magdeburg, Germany	<i>Advanced Nanoscale Characterization of Nitride-Based Heterostructures</i>
Abstract	We will present nano-scale correlation of structural, electronic and optical properties of nitride-based heterostructures using cathodoluminescence and electron-beam induced current directly performed in a scanning transmission electron microscope. Typical results exhibiting the complex nano-transport of excess carriers, in particular charge carriers and/or excitons, due to a specific heterostructure design of a device will be presented.	
S6. III-N Defect Control and Surface Effects		
@3rd Lecture Room, B1F		
Time	Speaker	Title
15:00-15:30	<b>Prof. Chris G. Van de Walle</b> University of California, Santa Barbara, USA	<i>Impact of polarization fields on surface reconstructions</i>
Abstract	<p>Polarization fields due to spontaneous and piezoelectric polarization are a distinguishing feature of nitride semiconductors. They are exploited in transistors to create high-density carrier gases, while in light emitters they need to be controlled to avoid efficiency loss. The impact of polarization on growth of nitrides has received less attention, however. We have recently developed a first-principles methodology that enables us to rigorously address polarization fields in surface calculations. The results show that spontaneous polarization affects the stability and nature of surface reconstructions. Compensation of the polarization fields requires the presence of significant amounts of charge, which manifests in the form of fixed charge associated with surface reconstructions or the presence of heterovalent impurities. Consequences for defect incorporation will be discussed.</p> <p>Work performed in collaboration with C. E. Dreyer, J. Neugebauer, M. Todorova, S. H. Yoo, and D. Vanderbilt.</p> <p>[1] S. H. Yoo, M. Todorova, J. Neugebauer, and C. G. Van de Walle, Phys. Rev. Appl. 19, 064037 (2023).</p>	

S9. III-N Spin-related Phenomena

@3rd Lecture Room, B1F

Time	Speaker	Title
13:00-13:30	<p><b>Prof. Jesús Zúñiga Pérez</b> Nanyang Technological University, Singapore (PAP, SPMS)</p>	<p><i>Quantum sensing with hexagonal BN</i></p>
<p>Abstract</p>	<p>Point defects in crystalline materials can behave as artificial atoms, with optical and spin properties that enable their exploitation in quantum sensing. Compared to bulk materials, where point defects are generally located far from the surface (which improves their stability and minimizes surface-induced charge and spin noises), in 2D materials point defects lie necessarily close to the surface. This allows to place the sensing probes as close as possible to the test object, without necessarily degrading neither their stability nor their sensing performance. Among the plethora of 2D materials, hBN occupies an outstanding place, given its ubiquitous presence in almost every 2D-based device and heterostructure. Interestingly, hBN hosts several types of spin-defects; among them, the negatively-charged boron vacancy (VB<sup>-</sup>) is the most studied one because, even though it shows a relatively poor luminescence intensity, it works at 300K and its spin can be initialized and read-out. In this work we will introduce the use of VB<sup>-</sup> in hBN for quantum strain sensing [1]. The measurement of optically-detected magnetic resonance (ODMR) on VB<sup>-</sup> ensembles enables to achieve sub-micrometre spatial resolution that, combined with micro-Raman spectroscopy, can provide a spatially-resolved map of in-plane and out-of-plane strain distribution [1]. Subsequently, we will address the important issue of enhancing photon emission from VB<sup>-</sup> defects. To achieve such an enhancement, we will implement metallic (gold-based) nanotrenches in which the coupled effect of gap-plasmons and enhanced extraction efficiency results in a ~ 40-times emission enhancement with respect to a bare gold surface, while being compatible with ODMR measurements [2]. Finally, we will discuss the possibility of substituting the conventional optical detection by an electrical one, promoting thereby hBN as a practical real-field quantum sensor [3].</p> <p>[1] X. Lyu et al., Nano Lett. 22 (2022) 6553</p> <p>[2] H. Cai et al., Nano Lett. 23 (2023) 4991</p> <p>[3] S. Ru et al., to be published</p>	

Day 2-November 11 (Tuesday)

S2. III-N Epitaxial Growth Techniques		
@2nd Lecture Room, B1F		
Time	Speaker	Title
15:00~15:30	Prof. Hideto Miyake 三宅 秀人 Mie University, Japan	<i>Polarity control of AlN via a combination of sputtering deposition and face-to-face annealing</i>
Abstract	<p>We have successfully fabricated high-quality AlN templates by combining sputtering deposition of AlN (Sp-AlN) with high-temperature face-to-face annealing (FFA). These templates are hereafter referred to as FFA Sp-AlN. Additionally, we achieved Al-polar and N-polar FFA Sp-AlN by annealing Sp-AlN films sputtered using a sintered AlN target and an Al metal target, respectively. By controlling the polarity, we fabricated a bilayer polarity-inverted AlN structure, where the Al-polar FFA Sp-AlN serves as the lower layer and the N-polar FFA Sp-AlN as the upper layer. In this bilayer polarity-inverted FFA Sp-AlN, an inversion domain boundary (IDB) with an abrupt interface, consisting of several monolayers (ML), and an atomically smooth surface were observed. Various devices have been proposed using polarity inversion structures, such as second harmonic generation (SHG) devices based on quasi-phase matching, which exploits the nonlinear optical properties of nitride semiconductors. Leveraging the structural characteristics of the bilayer polarity-inverted FFA Sp-AlN, an SHG device with a transverse quasi-phase matched waveguide was fabricated. This device achieves a high nonlinear coupling coefficient by placing IDBs at the nodes of the second harmonic (SH) wave electric field distribution. The fabrication of a multi-layer polarity-inverted AlN structure with more than two layers is highly desirable. In this study, we demonstrate the fabrication of a four-layer polarity-inverted AlN structure using multiple sputtering of AlN and FFA with the polarity control method of FFA Sp-AlN. It was found that the IDB structures vary depending on the sequence of polarity inversion.</p>	
S3. III-N Ternary and Quaternary Alloys		
@2nd Lecture Room, B1F		
Time	Speaker	Title
13:00~13:30	Prof. Mitsuru Funato 船戸 充 Kyoto University, Japan	<i>InGaN MOVPE on arbitrary 3D GaN templates for polychromatic emission</i>
Abstract	<p>InGaN grown on (0001) vicinal surface shows In-content variations depending on the inclination angle. This property leads to polychromatic emission from InGaN quantum well emitters grown on 3D GaN templates. Controlling the 3D shape enables us to tune the</p>	

	emission spectra, which is beneficial for the fabrication of polychromatic, full color light emitters via single-step crystal growth.	
<b>S7. III-N Optical and Electrical Properties</b>		
<b>@3rd Lecture Room, B1F</b>		
Time	Speaker	Title
15:00~15:30	<b>Prof. Yong-Hoon Cho</b> Korea Advanced Institute of Science and Technology (KAIST), South Korea	<i>Growth Control and Optical Characteristics of 6-fold and 3-fold Symmetric GaN Pyramid and Pillar Structures for Quantum Photonic Device Applications</i>
Abstract	<p>We developed III-nitride quantum dot (QD) uniform arrays using MOCVD, forming single InGaN QDs at the apex of six-fold and three-fold symmetric GaN pyramids via a self-limited growth mechanism. This method enables precise control of QD position, size, and symmetry, crucial for high-purity single-photon and polarization-entangled photon generation.</p> <p>We also fabricated GaN hexagonal microrods and triangular prisms supporting whispering gallery and superscar modes, respectively, achieving room-temperature exciton-polariton condensation. These advances in QD symmetry control and microcavity engineering pave the way for integrated quantum photonic and polaritonic devices.</p>	
15:30~16:00	<b>Dr. Sai Charan Vanjari</b> University of Bristol, UK	<i>The power race: GaN, SiC, or Ga2O3?</i>
Abstract	<p>Gallium nitride (GaN) has become central to wide band gap power electronics, with decades of progress driving its adoption in sub-1kV applications and establishing it as a preferred choice for low-voltage systems. Silicon carbide (SiC) currently dominates the 1-3kV range, while gallium oxide (Ga2O3), with its ultra-wide band gap and higher breakdown strength, promises operation beyond both GaN and SiC. This raises a key question: which material will shape the future of high-voltage power electronics?</p> <p>This talk will compare GaN, SiC and Ga2O3 across different voltage regimes, highlighting their performance advantages as well as key challenges in reliability, scalability and thermal management. Emphasis will be placed on high-voltage device architectures, defect-driven degradation, and emerging strategies such as heterogeneous integration, providing insights into pathways for next-generation, energy-efficient power conversion systems.</p>	

## S8. III-N Device Modeling and Simulation

@3rd Lecture Room, B1F

Time	Speaker	Title
13:00~13:30	<b>Prof. Yoshihiro Kangawa</b> 寒川 義裕 Kyushu University, Japan	<i>Optimal Design of Fabrication Process for Deep Ultraviolet Laser Diodes: Computational Approach</i>
Abstract	<p>Deep ultraviolet LDs and LEDs around 260 nm, which are absorbed by the RNA and DNA of viruses and bacteria, are expected to be useful. To enhance the emission efficiency of these optical devices, controlling the flatness of the heterointerface at the atomic level is essential. In this study, we investigated the relationship between the device fabrication process, specifically the growth temperature of thin films, and the flatness of the heterointerface using a computational approach.</p>	
13:30~14:00	<b>Dr. Muhammad Ajmal Khan</b> RIKEN, Japan	<i>Light Extraction Enhancement in 230 nm far-UVC LEDs Using nanoPSS and Photonic Crystals: Updates on Virus Inactivation</i>
Abstract	<p>Far-ultraviolet C (Far-UVC) light-emitting diodes (LEDs) operating near 230 nm are emerging as promising sources for safe and effective disinfection, including inactivation of airborne pathogens and viruses. However, their external quantum efficiency (EQE) remains below 1% @ 230nm emission wavelength, primarily due to poor light extraction efficiency (LEE) and point defects. In this talk, we present recent theoretical and experimental progress at RIKEN in collaboration with National Yang Ming Chiao Tung University (Taiwan) toward overcoming this limitation through nano-patterned sapphire substrates (nanoPSS) and photonic crystal (PhC) structures. Finite-difference time-domain (FDTD) simulations reveal that optimized nanoPSS and reflective PhCs can synergistically enhance LEE by up to 6.7× compared to flat substrates. Experimentally, nanoPSS-based devices demonstrated a two-fold increase in EQE—from 0.15% to 0.32%—and doubled emission power. The experimental results of both the nanoPSS and PhC based LED will be revealed later. Furthermore, our 230 nm far-UVC LED modules successfully inactivated Dengue Virus (DENV), HIV-1, Influenza-A Virus (IAV), and SarsCoV-2 confirming their potential for real-world sterilization applications. Ongoing work aims to integrate optimized PhC designs with nanoPSS to achieve EQE &gt;2% @ 230nm emission wavelength, paving the way for high-performance far-UVC LEDs for healthcare and environmental safety.</p>	

Day 3-November 12 (Wednesday)

S10. III-N Devices—FETs, LEDs, and Lasers		
@3rd Lecture Room, B1F		
Time	Speaker	Title
09:15~09:45	Prof. Tetsuya Takeuchi 竹内 哲也 Meijo University, Japan	<i>Highly efficient GaN-based vertical-cavity surface-emitting lasers</i>
Abstract	The developments towards higher wall-plug efficiency GaN-based VCSELs at Meijo University are described. By using high-quality AlInN/GaN DBR, lateral optical/current confinement, and in situ cavity length control, our GaN-based VCSELs show a WPE of 27% at 413 nm under RT CW operation.	
Special Session. Ultrawide-bandgap materials and devices		
@2nd Lecture Room, B1F		
Time	Speaker	Title
09:15~09:45	Prof. Masataka Higashiwaki 東脇 正高 Osaka Metropolitan University, Japan	<i>Nitrogen doping technology for Ga<sub>2</sub>O<sub>3</sub> devices</i>
Abstract	Nitrogen (N) atoms doped in gallium oxide (Ga <sub>2</sub> O <sub>3</sub> ) act as deep acceptors, and an energy barrier of about 3 eV can be formed at the N-doped p-Ga <sub>2</sub> O <sub>3</sub> /n-Ga <sub>2</sub> O <sub>3</sub> junction. In this talk, we will present the effect of N radical irradiation on electrical properties of Ga <sub>2</sub> O <sub>3</sub> Schottky barrier diodes and electrical properties of N-doped Ga <sub>2</sub> O <sub>3</sub> thin films grown by molecular beam epitaxy.	
09:45~10:15	Prof. Okhyun Nam Tech University of Korea, South Korea	<i>Recent Advances in Heteroepitaxial Diamond: From Single Crystal Substrate to Devices</i>
Abstract	<p>In our study, the activities for the growth of large size single crystal diamond substrate have been conducting using the heteroepitaxy on the foreign substrate. In case of (100) plane, we achieved the heteroepitaxy of free-standing single crystal diamond wafer (size: 20x20 mm<sup>2</sup>) on the A-plane sapphire substrate in the last year [1-2], and are working on the heteroepitaxy of larger-size diamond wafer (&gt;1inch).[3] Especially, the twin-free (111) single crystal diamond heteroepitaxy has been successfully demonstrated on the r-plane sapphire substrate, for the first time.[3]</p> <p>In addition, the heteroepitaxial single crystal diamond-based device study has been successfully conducted in the area of doping and devices of p-SBDs and p-MESFETs [4-5].</p>	

	<p>Recently, the H-terminated diamond E-/D-mode MOSFETs have been simultaneously fabricated on the same heteroepitaxial diamond substrate [6]. The detailed advancements in the heteroepitaxial diamond wafer and power devices will be discussed in the conference.</p>
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**ISGN-8**

November 9-12, 2025

NCKU, Taiwan

# Technical Program

# S1. III-N Bulk Crystal Growth

Oral Session: 2nd Lecture Room 第二演講室 (B1F)

Poster Session: Multifunction Room 多功能廳 (1F)

## Oral Session I: 13:00-14:45, Monday, November 10, 2025

### Presider:

Prof. Ming-Chi Mitch Chou (National Cheng Kung University, Taiwan)

Dr. Michał Boćkowski (Institute of High-Pressure Physics, Polish Academy of Sciences, Poland)

• 13:00 2025-Mon-S0101-I001

### Invited Talk

#### The Science and Art of GaN Crystal Growth

Dr. Michał Boćkowski, Institute of High-Pressure Physics, Polish Academy of Sciences, Poland

• 13:30 2025-Mon-S0101-O001

Manuscript ID: 0107

### Iwińska Award Candidate (Paper Competition)

#### Novel GaN Seed Architecture for Bulk Crystal Growth Processes Based on Surface Bonding

Krzysztof Gołyga, Jan Mizeracki, Magdalena A. Zając, Michał Fijałkowski, Robert Kucharski, Tomasz Sochacki, Michał Boćkowski, Institute of High Pressure Physics, Polish Academy of Sciences; Kacper Sierakowski, Department of Material Science and Engineering, North Carolina State University

• 13:45 2025-Mon-S0101-O002

Manuscript ID: 0064

### Iwińska Award Candidate (Paper Competition)

#### Correlation between reactor polycrystal amount and large pit formation in GaN growth by oxide vapor phase epitaxy

Naoki Fujimoto, Shigeyoshi Usami, Masayuki Imanishi, Mihoko Maruyama, Yusuke Mori, Graduate School of Eng, The University of Osaka; Masashi Yoshimura, Institute of Laser Engineering, The University of Osaka; Tomoaki Sumi, Junichi Takino, Yoshio Okayama, Panasonic Holdings; Masahiko Hata, Itochu Plastics Incorporated; Masashi Isemura, Soshō-Oshin Incorporated

• 14:00 2025-Mon-S0101-O003

Manuscript ID: 0065

### Iwińska Award Candidate (Paper Competition)

#### Dependence of thermal conductivity on oxygen concentration in GaN grown by OVPE method

Kosei Asao, Shigeyoshi Usami, Masayuki Imanishi, Mihoko Maruyama, Yusuke Mori, Graduate School of Eng, The University of Osaka; Junichi Takino, Tomoaki Sumi, Yoshio Okayama, Panasonic Holdings; Masashi Yoshimura, Institute of Laser Engineering, The University of Osaka; Masahiko Hata, Itochu Plastics Incorporated; Masashi Isemura, Soshō-Oshin Incorporated

• 14:15 2025-Mon-S0101-O004

Manuscript ID: 0087

#### Stability and Crystallization of hBN from 10 at.% B-Ni Solutions under Controlled N<sub>2</sub> Pressure

Petro Sadovyi, Bohdan Sadovyi, Stanislaw Krukowski, Sylwester Porowski, Izabella Grzegory, Institute of High Pressure Physics Polish Academy of Sciences, 29/37, Sokolowska street, 01-142 Warsaw, Poland; Andrii Nikolenko, Viktor Strelchuk, V. Lashkaryov Institute of Semiconductor Physics of National Academy of Sciences

of Ukraine, 41 pr. Nauky, 03028, Kyiv, Ukraine; Borys Turko, Ivan Franko National University of Lviv, Faculty of Physics, 50, Drahomanovastreet, Lviv, 79005, Ukraine

• 14:30 2025-Mon-S0101-O005

*Manuscript ID: 0096*

**N-polar epitaxial lateral overgrowth of GaN via high temperature Cl<sub>2</sub>-based halide vapor phase epitaxy**

Hisashi Murakami, Qiu Ping, Keito Shiroma, Haruto Ishida, Tokyo University of Agriculture and Technology; Aina Hiyama Zazuli, Narihito Okada, Yamaguchi University

### Oral Session II: 15:00-15:30, Monday, November 10, 2025

**Presider:**

Prof. Ming-Chi Mitch Chou (National Cheng Kung University, Taiwan)

Dr. Michał Bockowski (Institute of High-Pressure Physics, Polish Academy of Sciences, Poland)

• 15:00 2025-Mon-S0108-O001

*Manuscript ID: 0081*

**Iwińska Award Candidate (Paper Competition)**

**Surface Planarization and Reduction of Threading Dislocation Density of GaN Crystals after Facet Growth in the Na-flux Method**

Shogo Washida, Masayuki Imanishi, Ryotaro Sasaki, Kosuke Murakami, Shigeyoshi Usami, Mihoko Maruyama, Yusuke Mori, Graduate. School of Engineering., the University of Osaka; Masashi Yoshimura, Graduate. School of Engineering., the University of Osaka, Institute of Laser Engineering, the University of Osaka

• 15:15 2025-Mon-S0108-O002

*Manuscript ID: 0018*

**Fabrication of Needle-like AlN Seed Crystals and Epitaxial Growth using Fe-based Fluxes**

Sen Li, Chiaki Amei, Masayoshi Adachi, Makoto Ohtsuka, Hiroyuki Fukuyama, Institute of Multidisciplinary Research for Advanced Materials, Tohoku University, Japan

### Poster Session: 15:00~17:00, Tuesday, November 11, 2025

2025-Tue-P0101-P001

*Manuscript ID: 0071*

**3D CFD Study of Internal Installation Geometry Effects on Convective Transport and GaN Crystal Growth in the Ammonothermal Process**

Marek Zak, Pawel Kempisty, Boleslaw Lucznik, Robert Kucharski, Michał Bockowski, Institute of High Pressure Physics Polish Academy of Sciences, Poland

2025-Tue-P0101-P002

*Manuscript ID: 0093*

**From Crystal to Wafer: Advanced Mechanical Processing of Ammonothermal GaN**

Tomasz Sochacki, Robert Kucharski, Karolina Grabianska, Aneta Sidor-Zak, Jaroslaw Skladanowski, Grzegorz Kamler, Michał Bockowski, Institute of High Pressure Physics Polish Academy of Sciences

2025-Tue-P0101-P003

*Manuscript ID: 0102*

**Properties of defects formed as a result of hillock coalescence in Am- and HVPE-grown GaN crystals.**

Zajac A. Magdalena, Sochacki Tomasz, Kucharski Robert, Grabianska Karolina, Konczewicz Leszek, Zajac Marcin, Weyher L. Jan, Bockowski Michał, Institute of High Pressure Physics Polish Academy of Sciences, Warsaw, Poland; Paillet Matthieu, Juillaguet Sandrine, Contreras Sylvie, Laboratoire Charles Coulomb (L2C), University of Montpellier, CNRS, Montpellier, France; Stranak Patrik, Kirste Lutz, Fraunhofer Institute for Applied Solid State Physics (IAF), Freiburg, Germany.

2025-Tue-P0101-P004

*Manuscript ID: 0105*

**Thermodynamic Analysis of GaN Solubility in Supercritical Ammonia: Influence of Mineralizer Concentration and Pressure**

Pawel Kempisty, Karolina Grabianska, Robert Kucharski, Mikolaj Amilusik, Tomasz Sochacki, Michal Bockowski, Institute of High Pressure Physics Polish Academy of Sciences, Warsaw, Poland

2025-Tue-P0101-P005

*Manuscript ID: 0011*

**Bragg Diffraction Imaging Analysis of Crystal Defects in AlN Substrates**

L. Kirste, Fraunhofer Institute for Applied Solid State Physics (IAF), Freiburg, Germany; T.N. Tran-Caliste, J. Baruchel, European Synchrotron Radiation Facility (ESRF), Grenoble, France; C. Richter, T. Straubinger, C. Hartmann, Leibniz-Institut für Kristallzüchtung (IKZ), Berlin, Germany; M. Kabukcuoglu, Institute for Photon Science and Synchrotron Radiation (IPS), KIT, Karlsruhe, Germany

2025-Tue-P0101-P006

*Manuscript ID: 0057*

**Analysis of Growth Discontinuities in Ammonothermal GaN Crystals Using Bragg Diffraction Imaging**

L. Kirste, P. Straňák, Fraunhofer Institute for Applied Solid State Physics (IAF), Freiburg, Germany; T. Sochacki, R. Kucharski, K. Grabianska, J.L. Weyher, M. Bockowski, Institute of High Pressure Physics (UNIPRESS), Polish Academy of Sciences, Warsaw, Poland; T.N. Tran-Caliste, J. Baruchel, European Synchrotron Radiation Facility (ESRF), Grenoble, France

## S2. III-N Epitaxial Growth Techniques

Oral Session: 2nd Lecture Room 第二演講室 (B1F)

Poster Session: Multifunction Room 多功能廳 (1F)

### Oral Session: 15:00-17:15, Tuesday, November 11, 2025

**Presider:**

Prof. Chun-Kai Wang (National Kaohsiung University of Science and Technology, Taiwan)

Prof. Hideto Miyake (Mie University, Japan)

• 15:00 2025-Tue-S0204-I001

**Invited Talk**

**Polarity control of AlN via a combination of sputtering deposition and face-to-face annealing**

Prof. Hideto Miyake, Professor, Mie University, Japan

• 15:30 2025-Tue-S0204-O001

Manuscript ID: 0108

**Structural Evaluation of AlGa<sub>N</sub> MQWs on Face-to-Face Annealed (11-22) AlN Templates**

Hiroki Yasunaga, Kensei Oya, Ryota Akaike, Yongzhao Yao, Hideto Miyake, Mie University

• 15:45 2025-Tue-S0204-O002

Manuscript ID: 0073

**Crystallographic Orientation Control of Nonpolar AlN via Thermal Treatment of r-Plane Sapphire Substrates**

Shinnosuke Mori, Ryota Akaike, Hiroki Yasunaga, Takao Nakamura, Hideto Miyake, Mie University

• 16:00 2025-Tue-S0204-O003

Manuscript ID: 0027

**Calibration of Surface Temperature of Metallic Substrates in MBE – Unveiling the Impact of Thickness Dependent Emissivity of Thin Buffer Layers**

Z.R. Zytkeiwicz, K. Olszewski, A. Wierzbicka, M. Sobanska, Institute of Physics, Polish Academy of Sciences, Warsaw, Poland; M. Guziewicz, Łukasiewicz Research Network - Institute for Microelectronics and Photonics, Warsaw, Poland

• 16:15 2025-Tue-S0204-O004

Manuscript ID: 0074

**Estimation of Screw Dislocation Density in High-crystallinity AlN by X-ray Rocking Curves**

Renosuke Hara, Ryota Akaike, Hiroki Yasunaga, Takao Nakamura, Hideto Miyake, Mie University

• 16:30 2025-Tue-S0204-O005

Manuscript ID: 0025

**Growth Behavior of AlN Crystals Using Type 304L Stainless Steel Flux**

Makoto OHTSUKA, Masayoshi ADACHI, Hiroyuki FUKUYAMA, Institute of Multidisciplinary Research for Advanced Materials, Tohoku University

• 16:45 2025-Tue-S0204-O006

Manuscript ID: 0030

### Effect of Nb Addition to Molten Fe on Solution Growth of AlN Crystals

Shunya Nanri, Makoto Ohtsuka, Masayoshi Adachi, Hiroyuki Fukuyama, Institute of Multidisciplinary Research for Advanced Materials, Tohoku University

• 17:00 2025-Tue-S0204-O007

*Manuscript ID: 0138*

### Evaluation of Polarity-inverted AlN interface using oxidation processes

Tomohiro Tamano, Ryota Akaike, Hiroki Yasunaga, Hideto Miyake, Mie University; Zentaro Akase, Shigetaka Tomiya, Nara Institute of Science and Technology

## Poster Session: 15:00~17:00, Tuesday, November 11, 2025

2025-Tue-P0201-P001

*Manuscript ID: 0033*

### Effect of Flux Composition on Growth Behavior of AlN Crystals Using Fe-Cr-Ni Fluxes

Go Shinnoda, Masayoshi Adachi, Makoto Ohtsuka, Hiroyuki Fukuyama, IMRAM, Tohoku Univ.

2025-Tue-P0201-P002

*Manuscript ID: 0067*

### Buffer Layer Design toward 1600 V GaN HEMTs on 150 mm Si Substrates

Shao-Hsiang Hsu, Si-Hong Chen, Chieh-Hsiang Kuo, Jun-Zhe Wang, Hung-Yang Lin, Sheng-Kai Chen, Jen-Inn Chyi, National Central University, Taoyuan, Taiwan; Yong-Xiang Zhuang, Hsien-Chin Chiu, Chang Gung University, Taoyuan, Taiwan

2025-Tue-P0201-P003

*Manuscript ID: 0080*

### Performance Enhancement of AlGaIn/GaN HEMTs on 150 mm Si Substrates by B<sub>0.2</sub>GaN Buffer Layers

Hung-Yang Lin, Jun-Zhe Wang, Shao-Hsiang Hsu, Chao-Yuan Chang, Sheng-Kai Chen, Jen-Inn Chyi, National Central University, Taoyuan, Taiwan; Wei-Jen Hsueh, WAFER WORKS, Taoyuan, Taiwan

2025-Tue-P0201-P004

*Manuscript ID: 0113*

### Direct growth of Bulk InGaIn nanocolumns on nanotemplates prepared using Ni nanodot mask

Satoshi Ishikawa, Rie Togashi, Katsumi Kishino, Sophia University

2025-Tue-P0201-P005

*Manuscript ID: 0114*

### Influence of Underlying GaN Nanocolumns on the Selective Area Growth of GaInN

Takuto Katogi, Ryuta Shindo, Takumi Umemoto, Tomohiro Yamaguchi, Tohru Honda, Takeyoshi Onuma, Kogakuin university; Rie Togashi, Katsumi Kishino, Sophia university

2025-Tue-P0201-P006

*Manuscript ID: 0115*

### Surface Stoichiometry Control in GaN Pulsed Sputtering Epitaxy Using Sintered Target

Kohei Nomura, Masahiro Uemukai, Tomoyuki Tanikawa, Ryuji Katayama, The University of Osaka; Koo Bando, Yoshihiro Ueoka, Yoshiro Kususe, Masami Mesuda, Tosoh Corporation

2025-Tue-P0201-P007

*Manuscript ID: 0124*

**USPD-Fabricated Li-Doped p-NiO<sub>x</sub> Gates for High-Performance Normally-Off InAlGa<sub>N</sub>/Ga<sub>N</sub> HEMTs**

Yu-Hsuan Chen, Yan-Kuei Wu, Wei-Chou Hsu, National Cheng Kung University

2025-Tue-P0201-P008

*Manuscript ID: 0134*

**Growth and characterization of N-polar AlN and strained GaN heterostructures by MOVPE**

Yoann ROBIN, Itsuki Furuhashi, Xu Yang, Markus Pristovsek, Institute of Materials and Systems for Sustainability (IMaSS), Nagoya University, Japan

# S3. III-N Ternary and Quaternary Alloys

Oral Session: 2nd Lecture Room 第二演講室 (B1F)

Poster Session: Multifunction Room 多功能廳 (1F)

## Oral Session: 13:00-14:45, Tuesday, November 11, 2025

### Presider:

Prof. Chia-Yen Huang (National Yang Ming Chiao Tung University, Taiwan)

Prof. Mitsuru Funato (Kyoto University, Japan)

• 13:00 2025-Tue-S0303-I001

### Invited Talk

**InGaN MOVPE on arbitrary 3D GaN templates for polychromatic emission**

Prof. Mitsuru Funato, Professor, Kyoto University, Japan

• 13:30 2025-Tue-S0303-O001

Manuscript ID: 0098

**Challenges and Solutions in the Epitaxy of Al-rich AlGaN HEMT for Extreme Environmental Electronics**

Okhyun Nam, Jooyong Park, S. Mohan, J. Jeong, Tech University of Korea

• 13:45 2025-Tue-S0303-O002

Manuscript ID: 0026

**Attractive Ferroelectric Properties of Monocrystalline Sc-Rich Nitride Solid Solutions Grown by MBE**

Samuel Yang, Shubham Mondal, Jae Hun Kim, Zetian Mi, University of Michigan

• 14:00 2025-Tue-S0303-O003

Manuscript ID: 0068

**MOVPE of AINP/GaN HFET layer structures using PH3**

Eberhard Richter, Frank Brunner, Sanowar Alam Gazi, Sylvia Hagedorn, Oliver Hilt, Carsten Netzel, Kornelius Tetzner, Markus Weyers, Ferdinand-Braun-Institut (FBH), 12489 Berlin, Gustav-Kirchhoff-Str. 4, Germany

• 14:15 2025-Tue-S0303-O004

Manuscript ID: 0092

**Ammonothermal Growth of Bulk  $\text{Al}_x\text{Ga}_{1-x}\text{N}$ : Current Achievements and Perspectives for Crystal Development**

Kucharski Robert, Sochacki Tomasz, Grabianska Karolina, Zajac A. Magdalena, Jaroszynska Arianna, Weyher L. Jan, Institute of High Pressure Physics Polish Academy of Sciences; Stranak Patrik, Kirste Lutz, Fraunhofer Institute for Applied Solid State Physics (IAF); Bockowski Michal, Institute of High Pressure Physics Polish Academy of Sciences

• 14:30 2025-Tue-S0303-O005

Manuscript ID: 0109

**Influence of Strain on Hole Transport and TM-TE Emission in AlGaIn UVC LEDs with Direct Localization Landscape Model Calculation**

Yu-Ming Chang, Ping-Jie Zhuang, Yuh-Renn Wu, GIPO, National Taiwan University

Poster Session: 15:00~17:00, Tuesday, November 11, 2025

2025-Tue-P0301-P001

*Manuscript ID: 0091*

**Al<sub>x</sub>Ga<sub>1-x</sub>N growth by Halide Vapor Phase Epitaxy**

Arianna Jaroszynska, Karol Pozyczka, Petro Sadovyi, Robert Kucharski, Pawel Kempisty, Michal Bockowski, Tomasz Sochacki, Institute of High Pressure Physics, Polish Academy of Sciences; Lutz Kirste, Fraunhofer Institute for Applied Solid State Physics (IAF)

## S4. III-N Nanostructures and 2D Materials

Oral Session: 3rd Lecture Room 第三演講室 (B1F)

Poster Session: Multifunction Room 多功能廳 (1F)

### Oral Session I: 13:30-14:45, Monday, November 10, 2025

**Presider:**

Prof. Yu-Hsun Chou (National Cheng Kung University, Taiwan)

Prof. Jesús Zúñiga Pérez (Nanyang Technological University, Singapore)

• 13:30 2025-Tue-S0303-I001

**Invited Talk**

**The Optical Properties of Various Polytypes of  $sp^2$ -bonded Boron Nitride.**

Dr. Bernard Gil, Director of Research, CNRS, University of Montpellier, France

• 14:00 2025-Tue-S0303-O001

Manuscript ID: 0041

**(Al,Ga)N heterostructures grown on AlN on Graphene: towards van der Waals epitaxy of UV LED structures**

Julien Brault, Sunanda Mitra, Sébastien Chenot, Mohamed Al Khalfioui, Université Côte d'Azur, CNRS, CRHEA, Valbonne, 06560, France; Yuma Doko, Graduate School of Engineering, University of Fukui, Bunkyo, Fukui, Japan; Hideaki Kitahara, Masahiko Tani, Akihiro Hashimoto, Research Center for Development of Far Infrared Region, University of Fukui, 3-9-1 Bunkyo Fukui, 910-8507, Japan

• 14:15 2025-Tue-S0303-O002

Manuscript ID: 0028

**Peculiarities of MBE Growth and Properties of GaN Nanowires on Metallic ZrN Buffer Layers**

Marta Sobanska, Zbigniew R. Zytewicz, Karol Olszewski, Aleksandra Wierzbicka, Institute of Physics, Polish Academy of Sciences, Warsaw, Poland; Marek Guziewicz, Łukasiewicz Research Network - Institute for Microelectronics and Photonics, Warsaw, Poland

• 14:30 2025-Tue-S0303-O003

Manuscript ID: 0118

**Contactless Electreflectance Studies of Fermi Level Position at MXene/(Al)GaN Interface – Engineering of Electric Contacts to (Al)GaN**

Robert Kudrawiec, Wroclaw University of Science and Technology

### Poster Session: 15:00~17:00, Tuesday, November 11, 2025

2025-Tue-P0401-P001

Manuscript ID: 0005

**The Blood Test for Lung Cancer by InGaN Quantum Wells**

Kun-Yu Lai, Thuy Doan Khanh Huynh, Huy Kim Nhat, Fan-Ching Chien, National Central University; Yu-Chi Chiu, Taoyuan General Hospital; Yu-Chi Chiu, Yuanpei University of Medical Technology; Pin-Kuei Fu, Taichung Veterans General Hospital; Pin-Kuei Fu, National Chung Hsing University

2025-Tue-P0401-P002

*Manuscript ID: 0097*

**Growth of Boron Nitride on (100) Silicon Substrates**

Chen-Da Du, Kun-Yu Lai, National Central University

2025-Tue-P0401-P003

*Manuscript ID: 0054*

**Coupling between WSe<sub>2</sub> and Plasmonic Structure**

Chiao-Chih Lin, Program on Key Material, Academy of Innovative Semiconductor and Sustainable Manufacturing, National Cheng Kung University, Tainan, Taiwan; Zhe-Wei Hsu, Yu-Hsun Chou, Department of Photonics, National Cheng Kung University, Tainan, Taiwan

2025-Tue-P0401-P004

*Manuscript ID: 0052*

**Formation of non-polar and semi-polar AlN planes via microwave annealing of AlN on AAO templates**

Chien-Sheng Huang, Basheer Baba, Yi-Tang Lin, He-Han Wu, Che-Hao Liao, Department of Electronic Engineering, National Yunlin University of Science and Technology; Xiao Tang, School of Electrical, Electronic and Mechanical Engineering, University of Bristol

2025-Tue-P0401-P005

*Manuscript ID: 0076*

**Sensitivity Enhancement of Aluminum Nitride Surface Acoustic Wave Humidity Sensors Using Silica Nanospheres**

Che-Hao Liao, Lu-Xiang Wang, I-Ten Chen, Shih-Hung Lin, Chien-Sheng Huang, Department of Electronic Engineering, National Yunlin University of Science and Technology

# S5. III-N Heterostructure Characterization

Oral Session: 2nd Lecture Room 第二演講室 (B1F)

Poster Session: Multifunction Room 多功能廳 (1F)

## Oral Session: 15:30-17:00, Monday, November 10, 2025

### Presider:

Prof. Ming-Chi Mitch Chou (National Cheng Kung University, Taiwan)

Dr. Michał Boćkowski (Institute of High-Pressure Physics, Polish Academy of Sciences, Poland)

• 15:30 2025-Mon-S0509-I001

### Invited Talk

#### Advanced Nanoscale Characterization of Nitride-Based Heterostructures

Prof. Frank Bertram, Gordon Schmidt, Juergen, University of Magdeburg

• 16:00 2025-Mon-S0509-O001

Manuscript ID: 0062

#### Influence of 2D carrier localization on light emission in (Al,Ga)N alloys emitting in the Deep UV range.

Alexandra Ibanez, Bernard Gil, Guillaume Cassabois, Pierre Valvin, Wilfried Desrat, UMR 5221, Laboratoire Charles Coulomb and Université Montpellier 2, Montpellier, 34095, France; Nikita Nikitskiy, Julien Brault, Mathieu Leroux, Antoine Barbier, Fabrice Semond, CNRS-CRHEA, Université Côte d'Azur, Valbonne, 06560, France; Muhammad Khan, Hideki Hirayama, Fumiya Chugenji, Taiga Kirihara, RIKEN Cluster for Pioneering Research (CPR), 2-1 Hirosawa, Wako, Saitama 351-0198, Japan

• 16:15 2025-Mon-S0509-O002

Manuscript ID: 0003

#### Direct observation of nanoscopic lattice distortion and composition inhomogeneity in AlGaIn multiple-quantum wells

Chia-Yen Huang, National Yang Ming Chiao Tung University; Ying-Chun Chao, Hung-Wei Yen, National Taiwan University

• 16:30 2025-Mon-S0509-O003

Manuscript ID: 0048

### Iwińska Award Candidate (Paper Competition)

#### Enhanced Green Hydrogen Generation Using GO-GaN Photoanodes in Direct Seawater Splitting

Jeong-Kyun OH, Sung-Un Kim, Dae-Young Um, Min-Seok Lee, Cheul-Ro Lee, Yong-Ho Ra, . Division of Advanced Materials Engineering, College of Engineering, Jeonbuk National University (JBNU), Jeonju, Republic of Korea

• 16:45 2025-Mon-S0509-O004

Manuscript ID: 0104

### Iwińska Award Candidate (Paper Competition)

#### Defects Visualization in GaN-based HEMTs with SiNx nano-mask by Cathodoluminescence Spectroscopy

Tu Huynh Pham, Nhu Quynh Diep, Jinji Dai, Quynh Trang Tran, Thi Bich Tuyen Huynh, Wu Ching Chou, Department of Electrophysics, National Yang Ming Chiao Tung University, Hsinchu, Taiwan; Thi Thu Mai, Department of Advanced Materials Science and Nanotechnology, University of Science and Technology of Hanoi, Vietnam

**Poster Session: 15:00~17:00, Tuesday, November 11, 2025**

2025-Tue-P0501-P001

*Manuscript ID: 0035*

**Comparison of n-Ga<sub>2</sub>O<sub>3</sub>/p-GaN PN Heterojunction Diode Grown by TMGa and TEGa**

Ho, Ai, Chun-Kai Huang, Institute of Pioneer Semiconductor Innovation, National Yang Ming Chiao Tung University, Hsinchu 300, Taiwan; Sheng-Ti Chung, Ray-Hua Horng, Institute of Electronics, National Yang Ming Chiao Tung University, Hsinchu 300, Taiwan

2025-Tue-P0501-P002

*Manuscript ID: 0036*

**Effect of Post-Deposition Annealing on Room-Temperature Sputtered NiO Gate Dielectric for AlGaIn/GaN HEMTs**

Hao-Wei Chang, 0965003491; Po-Chuan Liao, qwert61004.ee12@nycu.edu.tw; Ray-Hua Horng, rayhua@nycu.edu.tw

# S6. III-N Defect Control and Surface Effects

Oral Session: 3rd Lecture Room 第三演講室 (B1F)

Poster Session: Multifunction Room 多功能廳 (1F)

## Oral Session: 15:00-17:00, Monday, November 10, 2025

### Presider:

Prof. Hsiang-Chen Wang (National Chung Cheng University, Taiwan)

Prof. Che-Hao Liao (National Yunlin University of Science and Technology, Taiwan)

• 15:00 2025-Mon-S0602-I001

### Invited Talk

#### Impact of polarization fields on surface reconstructions

Prof. Chris G. Van de Walle, Herbert Kroemer Distinguished Professor, Materials, University of California, Santa Barbara, USA

• 15:30 2025-Mon-S0602-O001

Manuscript ID: 0007

#### Vacancy-type defects in low-dose Si-implanted GaN probed by positron annihilation

H.Iguchi, Toyota Central R&D Labs; M. Horita, J. Suda, Nagoya University; K. Shima, S. F. Chichibu, Tohoku University; S. Ishibashi, University of Tsukuba

• 15:45 2025-Mon-S0602-O002

Manuscript ID: 0029

#### Investigating GaN-Based Avalanche Photodiode Performance with Different GaN Substrates and p-Layer Doping Profiles

Alexandra V. Dolgashev, Davide Balzerani, Zhiyu Xu, Theeradetch Detchprohm, Russell D. Dupuis, School of Electrical and Computer Engineering, Georgia Institute of Technology, Atlanta, Georgia 30332-0250, USA; Subhra Chowdhury, Dhruves Biswas, Magnolia Optical Technologies, Woburn, Massachusetts 01801 USA; Nepomuk Otte, School of Physics, Georgia Institute of Technology, Atlanta, Georgia 30332-0250, USA

• 16:00 2025-Mon-S0602-O003

Manuscript ID: 0046

#### High-quality MBE-grown AlN thin film layers on Sapphire substrates by high-temperature annealing

SUNANDA MITRA, MAUD NEMOZ, AIMERIC COURVILLE, Pierre-Marie Coulon, Jean-Yves Duboz, JULIEN BRAULT, Université Côte d'Azur, CNRS, CRHEA, 06560 Valbonne, France

• 16:15 2025-Mon-S0602-O004

Manuscript ID: 0112

#### Theoretical Study of AlGaN(0001) Surfaces under MOVPE Growth Conditions: Surface Reconstructions, Potential Energy Maps, and Diffusion

Karol Kawka, Pawel Strak, Pawel Kempisty, Institute of High Pressure Physics of the Polish Academy of Sciences, Warsaw, Poland

• 16:30 2025-Mon-S0602-O005

Manuscript ID: 0085

**Electrical compensation and acceptor-type carrier traps in nitride semiconductors**

Igor Prozheev, Ilja Makkonen, Filip Tuomisto, Department of Physics and Helsinki Institute of Physics, University of Helsinki, P.O. Box 43, FI-00014 HELSINKI, FINLAND

• 16:45 2025-Mon-S0602-O006

Manuscript ID: 0024

**The Role of Native Oxide on p-type N-polar GaN Ohmic Contacts**

Chao-I (Benny) Liu, Masahiro Kamiyama, Cristyan Quiñones García, Shashwat Rathkanthiwar, Ronny Kirste, Ramón Collazo, Zlatko Sitar, Department of Materials Science and Engineering, North Carolina State University, Raleigh, North Carolina, USA; Matthew Alessi, Department of Electrical and Computer Engineering, North Carolina State University, Raleigh, North Carolina, USA; Pramod Reddy, Adroit Materials, Cary, North Carolina, USA

**Poster Session: 15:00~17:00, Tuesday, November 11, 2025**

2025-Tue-P0601-P001

Manuscript ID: 0021

**The performance comparison of GaN vertical transistors with sidewalls treated using TMAH and H3PO4 solutions**

Ting-Ci Li, Yu-Chuan Chu, Zhi-Xiang Zhang, Chih-Kang Chang, Jian-Jang Huang, Graduate Institute of Photonics and Optoelectronics, National Taiwan University

2025-Tue-P0601-P002

Manuscript ID: 0044

**Study on the Growth Mechanism of Periodic Structure MoS<sub>2</sub>**

Chin-Jen Huang, paullovealice@gmail.com; Kai-Hsiang Ke, dannykewade51@gmail.com; Ming-Chen Li, yoyo410508@gmail.com; Kuang-Yu Kung, kuangyu365@gmail.com; Chih-Hsin Tseng, chihhsin0322@gmail.com; Hsiang-Chen Wang, hcwang@ccu.edu.tw

2025-Tue-P0601-P003

Manuscript ID: 0045

**Fabrication of Cu<sub>2</sub>O Biosensor for Photoelectrochemical and Impedance Detection of Lung Cancer Cell**

Kuang-Yu Kung, kuangyu365@gmail.com; Quan-Han Gong, zxc60153.54345@gmail.com; Ming-Zhen Li, yoyo410508@gmail.com; Chin-Jen Huang, paullovealice@gmail.com; Chih-Hsin Tseng, chihhsin0322@gmail.com; Hsiang-Chen Wang, hcwang@ccu.edu.tw

2025-Tue-P0601-P004

Manuscript ID: 0055

**Fermi Level Pinning behaviour of semi-polar (10-11) n-GaN surface before and after passivation**

Jun-Young Kwon, Tae-Yeon Seong, Korea University; Hiroshi Amano, Nagoya University

2025-Tue-P0601-P005

*Manuscript ID: 0082*

**Vacancy defects in III-nitride alloys**

Filip Tuomisto, University of Helsinki

# S7. III-N Optical and Electrical Properties

Oral Session: 3rd Lecture Room 第三演講室 (B1F)

Poster Session: Multifunction Room 多功能廳 (1F)

Oral Session: 15:00-17:15, Tuesday, November 11, 2025

**Presider:**

Prof. Chan-Shan Yang (National Taiwan Normal University, Taiwan)

Prof. Hsin-Chieh Yu (National Yang Ming Chiao Tung University, Taiwan)

• 15:00 2025-Tue-S0704-I001

**Invited Talk**

**Growth Control and Optical Characteristics of 6-fold and 3-fold Symmetric GaN Pyramid and Pillar Structures for Quantum Photonic Device Applications**

Prof. Yong-Hoon Cho, Department of Physics and KI for the NanoCentury, Korea Advanced Institute of Science and Technology (KAIST), Daejeon, Republic of Korea

• 15:30 2025-Tue-S0704-I002

**Invited Talk**

**The power race: GaN, SiC, or Ga<sub>2</sub>O<sub>3</sub>?**

Dr. Sai Charan Vanjari, Prof. Martin Kuball, University of Bristol, UK

• 16:00 2025-Tue-S0704-O001

*Manuscript ID: 0040*

**Performance Enhancement of AlGaIn/GaN HEMTs by Ar<sup>+</sup> Ion Implantation with Pre-Annealing Process and CF<sub>4</sub> Surface Treatment**

Min-Chun, Chung, Kun-Yang Jhang, Ren-Hong Zhang, Graduate Institute of Photonics and Optoelectronics, National Taiwan University; Yi-Lun Huang, Graduate School of Advanced Technology, National Taiwan University

• 16:15 2025-Tue-S0704-O002

*Manuscript ID: 0012*

**Monolithic GaN meta-collimator on the backside of microlight emitting diodes**

Yu-Chi Lee, Vtin66067632v@gmail.com; Li-Sheng Hu, andyhu891209@gmail.com; Po-Yang Chang, jerome0425@gmail.com; Yu-Min Chang, chang.ym.ee11@nycu.edu.tw; Yao-Wei Huang, ywh@nycu.edu.tw; Chia-Yen Huang, cyhuang06@nycu.edu.tw

• 16:30 2025-Tue-S0704-O003

*Manuscript ID: 0106*

**Deep Magnesium Diffusion in Conductive Ammonothermal GaN for Thick Semi-Insulating Layer Fabrication**

Krzysztof Gołyga, Tomasz Sochacki, Arianna Jaroszyńska, Michał Fijałkowski, Karolina Grabiańska, Marcin Zajac, Julita Smalc-Koziorowska, Artur Lachowski, Michał Boćkowski, Institute of High Pressure Physics, Polish Academy of Sciences; Lutz Kirste, Patrik Stranak, Fraunhofer Institute for Applied Solid State Physics IAF; Kacper Sierakowski, Department of Material Science and Engineering, North Carolina State University; Rafał Jakieta, Institute of Physics, Polish Academy of Sciences; Marcin Turek, Institute of Physics, Maria Curie-Skłodowska University in Lublin; Kensuke Sumida, Graduate School of Engineering, Nagoya University

• 16:45 2025-Tue-S0704-O004

*Manuscript ID: 0066*

### **Ultra-High Brightness Blue Quantum Dot Light-Emitting Diodes with Charge Control Layer**

You-Huei Jhang, Min-Han Lu, Institute of Photonic System, College of Photonics, National Yang Ming Chiao Tung University, Tainan 711, Taiwan; Zheng-Wei Lu, Shoou-Jinn Chang, Program on Semiconductor Manufacturing Technology, Academy of Innovative Semiconductor and Sustainable Manufacturing, National Cheng Kung University, University Road, Tainan City 701, Taiwan; Yu-Heng Hong, Hao-Chung Kuo, Hon Hai Research Institute, New Taipei City 236, Taiwan; Hsin-Chieh Yu, Program on Semiconductor Manufacturing Technology, Academy of Innovative Semiconductor and Sustainable Manufacturing, National Cheng Kung University, University Road, Tainan City 701, Taiwan, Institute of Lighting and Energy Photonics, College of Photonics, National Yang Ming Chiao Tung University, Tainan 711, Taiwan

• 17:00 2025-Tue-S0704-O005

*Manuscript ID: 0139*

### **Distinctness of Spontaneous Emission and Optical Gain in Wide InGaN Quantum Wells**

Greg Muziol, Mateusz Hajdel, Marcin Siekacz, Pawel Wolny, Czeslaw Skierbiszewski, Institute of High Pressure Physics PAS; Ulrich Theodor Schwarz, Chemnitz University of Technology

## **Poster Session: 15:00~17:00, Tuesday, November 11, 2025**

2025-Tue-P0701-P001

*Manuscript ID: 0034*

### **Investigation of (Al,Ga)N:Mg p-type doping using UV light excitation during molecular beam epitaxy growth**

Julien Brault, Sankesh Shetty, Satish Gupta, Sunanda Mitra, Sébastien Chenot, Mathieu Leroux, Mohamed Al Khalfioui, Université Côte d'Azur, CNRS, CRHEA, Valbonne, 06560, France; Samuel Matta, RIBER SA, 31 rue Casimir Perier, 95873 Bezons, France; Alexandra Ibanez, Leszek Konczewicz, Pierre Valvin, Guillaume Cassabois, Sylvie Contreras, Bernard Gil, UMR 5221, L2C and Université Montpellier 2, Montpellier, 34095, France; Takeshi Moriyasu, Hideaki Kitahara, Research Center for Development of Far Infrared Region, University of Fukui, 3-9-1 Bunkyo Fukui, 910-8507, Japan; Muhammad Ajmal Khan, Hideki Hirayama, Masahiko Tani, RIKEN Cluster for Pioneering Research (CPR), 2-1 Hirosawa, Wako, Saitama 351-0198, Japan

2025-Tue-P0701-P002

*Manuscript ID: 0050*

### **Photon Recycling-Driven Vertical Light Extraction in InGaN Nanorods for Advanced Micro-LED Efficiency**

Min-Seok Lee, Sung-Un Kim, Dae-Young Um, Jeong-Kyun Oh, Cheul-Ro Lee, Yong-Ho Ra, Division of Advanced Materials Engineering, College of Engineering, Jeonbuk National University (JBNU), Jeonju, Republic of Korea

2025-Tue-P0701-P003

*Manuscript ID: 0069*

### **Open-Circuit Voltage Methods to Detect Micro-LED Characteristics**

Fu-An Tu, mannydu.ee11@nycu.edu.tw; Ming-Hsien Wu, ITRI\_MHWu@itri.org.tw; Yen-Hsiang Fang, YHFang@itri.org.tw; Hao-Chung Kuo, hckuo0206@nycu.edu.tw; Chien-Chung Lin, chienchunglin@ntu.edu.tw

2025-Tue-P0701-P004

*Manuscript ID: 0121*

**Thickness-Dependent strain relaxation in Semipolar (11-22) AlN on m-Sapphire**

Bei Ma, Yoshihiro Ishitani, Chiba University; Kensei Oya, Ryota Akaike, Hideto Miyake, Mie University

# S8. III-N Device Modeling and Simulation

Oral Session: 3rd Lecture Room 第三演講室 (B1F)

Poster Session: Multifunction Room 多功能廳 (1F)

Oral Session: 13:00-14:45, Tuesday, November 11, 2025

**Presider:**

Prof. Ya-Ju Lee (National Cheng Kung University, Taiwan)

Prof. Yoshihiro Kangawa (Kyushu University, Japan)

• 13:00 2025-Tue-S0803-I001

**Invited Talk**

**Optimal Design of Fabrication Process for Deep Ultraviolet Laser Diodes: Computational Approach**

Prof. Yoshihiro Kangawa, Research Institute for Applied Mechanics, Kyushu University, Japan

• 13:30 2025-Tue-S0803-I002

**Invited Talk**

**Light Extraction Enhancement in 230 nm far-UVC LEDs Using nanoPSS and Photonic Crystals: Updates on Virus Inactivation**

Dr. Muhammad Ajmal Khan, Senior Research Scientist, RIKEN, Japan

• 14:00 2025-Tue-S0803-O001

*Manuscript ID: 0042*

**High RF Metrics and Gate-Length Scaling Behavior in InAlGa<sub>N</sub>/Ga<sub>N</sub> HEMTs Assessed by Small-Signal Modeling**

Kun-Yang Jhang, Min-Chun Chung, Ren-Hong Zhang, Graduate Institute of Photonics and Optoelectronics, National Taiwan University; Yi-Lun Huang, Graduate School of Advanced Technology, National Taiwan University

• 14:15 2025-Tue-S0803-O002

*Manuscript ID: 0110*

**Design Optimization of AlInGa<sub>N</sub>/Ga<sub>N</sub> HEMTs for High Frequency Operation**

Chia-Yu Hung, Yuh-Renn Wu, GIPO, National Taiwan University; Po-Tsung Tu, Electronic and Optoelectronic System Research Laboratories, Industrial Technology Research Institute, Hsinchu, Taiwan.

• 14:30 2025-Tue-S0803-O003

*Manuscript ID: 0119*

**Analysis of Vertical Ga<sub>N</sub> MOSFET with High Current Density for High-Power Applications**

Yi-Chen Ho, Yuh-Renn Wu, GIPO, National Taiwan University

**Poster Session: 15:00~17:00, Tuesday, November 11, 2025**

2025-Tue-P0801-P001

*Manuscript ID: 0038*

**Optical Gain Evolution and Field Screening in Wide Polar InGaN and AlGaN Quantum Wells**

Marta Gladysiewicz, Robert Kudrawiec, Wrocław University of Science and Technology

## S9. III-N Spin-related Phenomena

Oral Session: 3rd Lecture Room 第三演講室 (B1F)

Poster Session: Multifunction Room 多功能廳 (1F)

**Oral Session: 13:00-13:30, Monday, November 10, 2025**

**Presider:**

Prof. Yu-Hsun Chou (National Cheng Kung University, Taiwan)

Prof. Jesús Zúñiga Pérez (Nanyang Technological University, Singapore)

• 13:00 2025-Mon-S0906-I001

**Invited Talk**

**Quantum sensing with hexagonal BN**

Prof. Jesús Zúñiga Pérez, CNRS Research Director

# S10. III-N Devices—FETs, LEDs, and Lasers

Oral Session: 3rd Lecture Room 第三演講室 (B1F)

Poster Session: Multifunction Room 多功能廳 (1F)

## Oral Session: 09:15-11:30, Wednesday, November 12, 2025

### Presider:

Prof. Zhi-Ting Ye (National Chung Cheng University, Taiwan)

Prof. Tetsuya Takeuchi (Meijo University, Japan)

• 09:15 2025-Wed-S1005-I001

### Invited Talk

#### Highly efficient GaN-based vertical-cavity surface-emitting lasers

Prof. Tetsuya Takeuchi, Satoshi Kamiyama, Motoaki Iwaya, Meijo University

• 09:45 2025-Wed-S1005-O001

*Manuscript ID: 0088*

#### Low-voltage operation toward high-efficiency GaN-based vertical-cavity surface-emitting laser

Atsunori Tokushi, Naoki Shibahara, Shoki Arakawa, Taiki Kitamura, Tetsuya Takeuchi, Satoshi Kamiyama, Motoaki Iwaya, Department of Materials Science and Engineering, Meijo University

• 10:00 2025-Wed-S1005-O002

*Manuscript ID: 0020*

#### Vertical GaN MOSFETs with Body Trench Structure for Enhanced Electrical Performance

Jun-Xiang Wang, Zhi-Xiang Zhang, Chih-Kang Chang, Ting-Ci Li, Graduate Institute of Photonics and Optoelectronics, National Taiwan University; Jian-Jang Huang, Department of Electrical Engineering, National Taiwan University

• 10:15 2025-Wed-S1005-O003

*Manuscript ID: 0089*

#### Laser Lift Off via laser scanning toward high-efficiency UV-C LEDs

Sena Miura, Maho Fujita, Teppei Takehisa, Hibiki Muto, Kenta Takase, Marina Fujita, Haruto Hirota, Hisanori Ishiguro, Motoaki Iwaya, Satoshi Kamiyama, Tetsuya Takeuchi, Department of Materials Science and Engineering, Meijo Univ.; Yoshiki Saito, Koji Okuno, Toyoda Gosei Co., Ltd.

• 10:30 2025-Wed-S1005-O004

*Manuscript ID: 0061*

#### Step-Free Monolithic Integration of GaInN-Based Stacked RGB $\mu$ LEDs with Co-Planar Electrodes

Yuki Shimizu, Koko Fukushima, Keisuke Takeya, Yoshinobu Suehiro, Tetsuya Takeuchi, Satoshi Kamiyama, Motoaki Iwaya, Department of Materials Science and Engineering, Meijo University; Daisuke Iida, Kazuhiro Ohkawa, Electrical and Computer Engineering Programme, Computer, Electrical and Mathematical Sciences and Engineering Division, King Abdullah University of Science and Technology (KAUST)

• 10:45 2025-Wed-S1005-O005

*Manuscript ID: 0117*

**Far-Ultraviolet Second Harmonic Generation in Four-Layer Polarity Inverted AlN Channel Waveguide**

Eiki Sato, Hiroto Honda, Masahiro Uemukai, Tomoyuki Tanikawa, Ryuji Katayama, Graduate School of Engineering, The University of Osaka, Osaka 565-0871, Japan; Tomohiro Tamano, Hideto Miyake, Graduate School of Engineering, Mie University, Mie 514-8507, Japan; Kanako Shojiki, Graduate School of Engineering, Kyoto University, Kyoto 615-8510, Japan

• 11:00 2025-Wed-S1005-O006

*Manuscript ID: 0079*

**AlGa<sub>N</sub> homojunction tunnel junctions with Mg and Si concentrations over  $3 \times 10^{20} \text{cm}^{-3}$**

Hibiki Muto, Teppei Takehisa, Sena Miura, Marina Fujita, Kenta Takase, Haruto Hirota, Hisanori Ishiguro, Satoshi Kamiyama, Motoaki Iwaya, Tetsuya Takeuchi, Meijo Univ.

• 11:15 2025-Wed-S1005-O007

*Manuscript ID: 0137*

**High-Performance AlInGa<sub>N</sub>/Ga<sub>N</sub> HEMTs on 8 inch Ga<sub>N</sub>-on-Si Using CMOS BEOL-Compatible Processing**

Po-Tsung Tu, Po-Tsung Lee, Hao-Chung Kuo, Department of Photonics, National Yang Ming Chiao Tung University, Hsinchu, Taiwan.; Po-Tsung Tu, Po-Chun Yeh, Electronic and Optoelectronic System Research Laboratories, Industrial Technology Research Institute, Hsinchu, Taiwan.; Sheng-Kai Chen, Department of Electrical Engineering, National Central University, Taoyuan, Taiwan; Yuh-Renn Wu, Graduate Institute of Photonic and Optoelectronics and Department of Electrical Engineering,; Jen-Inn Chyi, Department of Electrical Engineering, National Central University, Taoyuan, Taiwan.

**Poster Session: 15:00~17:00, Tuesday, November 11, 2025**

2025-Tue-P1001-P001

*Manuscript ID: 0004*

**Directional Optimization of Resonant Cavity Micro Light-Emitting Diodes Using Multilayer DBR and Microlens Integration**

Chien-Chi Huang, Li-Yin Chen, Fang-Chung Chen, Department of Photonics, College of Electrical and Computer Engineering, National Yang Ming Chiao Tung University, Hsinchu 30010, Taiwan; Tzu-Yi Lee, Hao-Chung Kuo, Department of Photonics, College of Electrical and Computer Engineering, National Yang Ming Chiao Tung University, Hsinchu 30010, Taiwan and Semiconductor Research Center, Hon Hai Research Institute, Taipei 11492, Taiwan; Fu-He Hsiao, Semiconductor Research Center, Hon Hai Research Institute, Taipei 11492, Taiwan and Department of Electrophysics, College of Science, National Yang Ming Chiao Tung University, Hsinchu 30010, Taiwan; Kuo-Bin Hong, Chin-Wei Sher, Yu-Heng Hong, Semiconductor Research Center, Hon Hai Research Institute, Taipei 11492, Taiwan; Gong-Ru Lin, Graduate Institute of Photonics and Optoelectronics and the Department of Electrical Engineering, National Taiwan University, Taipei, Taiwan; Chia-Feng Lin, Department of Materials Science and Engineering, National Chung Hsing University, Taichung, Taiwan; Jr-Hau He, Department of Materials Science and Engineering, City University of Hong Kong, Tat Chee Avenue, Kowloon, Hong Kong

<p>2025-Tue-P1001-P002</p> <p><i>Manuscript ID: 0010</i></p> <p><b>Effect of air hole geometry on the optical properties of InGaN/GaN photonic crystal surface-emitting lasers</b></p> <p>Wen-Hsuan Hsieh, nickhsieh.ee08@nycu.edu.tw; Ching-Han Lin, kevin89112016@gmail.com; Chen-Yu Yang, alex.yang.ee13@nycu.edu.tw; Tien-Chang Lu, timtclu@nycu.edu.tw; Chia-Yen Huang, cyhuang06@nycu.edu.tw</p>
<p>2025-Tue-P1001-P003</p> <p><i>Manuscript ID: 0014</i></p> <p><b>Tunnel Junctions for New Architecture of Nitride Devices</b></p> <p>Czeslaw Skierbiszewski, Grzegorz Muziol, Mikolaj Zak, Marcin Siekacz, Marta Sawicka, Henryk Turski, Institute of High Pressure Physics PAS</p>
<p>2025-Tue-P1001-P004</p> <p><i>Manuscript ID: 0015</i></p> <p><b>Observation of Quasi-Saturation in Sidewall-Gate GaN Vertical Transistors</b></p> <p>Chih-Kang Chang, Zhi-Xiang Zhang, Ting-Ci Li, Jun-Xiang Wang, Jian-Jang Huang, Graduate Institute of Photonics and Optoelectronics, National Taiwan University</p>
<p>2025-Tue-P1001-P005</p> <p><i>Manuscript ID: 0019</i></p> <p><b>Impact of Indium/Aluminum Composition on DC Performance of InAlN/GaN HEMTs on Silicon Substrates</b></p> <p>Shyh-Jer Huang, Tzy-Yu Shen, Department of Electro-Optical Engineering, National Formosa University, Huwei Township, Yunlin County 632, Taiwan; Yu-Chen Liu, Yung-Wei Chen, Meng-Chyi Wu, Institute of Electronics Engineering, National Tsing Hua University, Hsinchu 30013, Taiwan; Chun-Yu Lin, Shi-Cheng Huang, Zi-Hao Wang, Yan-Kuin Su, Academy of Innovative Semiconductor and Sustainable Manufacturing, National Cheng-Kung University, Tainan 701, Taiwan.; Takashi Yoda, Takayuki Ohba, WOW Alliance, Institute of Science Tokyo, 4259 Nagatsuta, Midori-ku, Yokohama, 226-8503, Japan</p>
<p>2025-Tue-P1001-P006</p> <p><i>Manuscript ID: 0022</i></p> <p><b>Micro AlGaInP-based red light-emitting diode efficiency improvement by sidewall oxidation</b></p> <p>Shu-Han Yuan, Yuan-Chao Wang, Cheng-Jui Yu, Jian-Jang Huang, Graduate Institute of Photonics and Optoelectronics, National Taiwan University.</p>
<p>2025-Tue-P1001-P007</p> <p><i>Manuscript ID: 0043</i></p> <p><b>Direct correlation of structural and optical properties of a red-emitting InGaN/GaN Mini-LED</b></p> <p>Niklas Dreyer, Frank Bertram, Gordon Schmidt, Silke Petzold, Anja Dempewolf, Stefan Sterling, Juergen Christen, University of Magdeburg; Zhaoying Chen, Zexing Yuan, Yan Wang, Xinqiang Wang, Peking University</p>
<p>2025-Tue-P1001-P008</p> <p><i>Manuscript ID: 0047</i></p> <p><b>TEGa-Based Non-Recessed <math>\beta</math>-Ga<sub>2</sub>O<sub>3</sub> MOS Structure for High Breakdown Voltage Applications</b></p> <p>Jun-Ting Ye, justin201.ee13@nycu.edu.tw</p>

<p>2025-Tue-P1001-P009</p> <p><i>Manuscript ID: 0059</i></p> <p><b>Investigation of Normally-off InAlN/GaN HEMTs with Recessed Gate and p-type NiOx Gate Electrodes</b></p> <p>Ysui-Yu Hsieh, Chun-Yu Lin, Shi-Cheng Huang, Rong-Ming Ko, Zi-Hao Wang, Yan-Kuin Su, Academy of Innovative Semiconductor and Sustainable Manufacturing, National Cheng-Kung University, Tainan 701, Taiwan.; Jun-Wei Huang, Min-Han Li, Institute of Electronics Engineering, Department of Electrical Engineering, National Cheng Kung University, Tainan 701, Taiwan; Tzy-Yu Shen, Jian-Kai Chen, Shyh-Jer Huang, Department of Electro-Optical Engineering, National Formosa University, Huwei Township, Yunlin County 632, Taiwan</p>
<p>2025-Tue-P1001-P010</p> <p><i>Manuscript ID: 0060</i></p> <p><b>Fabrication and characterization of a stacked GaInN monolithic <math>\mu</math>LED array with a step-free structure</b></p> <p>Koko Fukushima, Yuki Shimizu, Keisuke Takeya, Yoshinobu Suehiro, Satoshi Kamiyama, Tetsuya Takeuchi, Motoaki Iwaya, Department of Materials Science and Engineering, Meijo University</p>
<p>2025-Tue-P1001-P011</p> <p><i>Manuscript ID: 0070</i></p> <p><b>275 nm Deep-Ultraviolet Light-Emitting Diodes with 9.1% Wall-Plug Efficiency</b></p> <p>Guo-Dong Hao, Manabu Taniguchi, Shin-ichiro Inoue, National Institute of Information and Communications Technology (NICT)</p>
<p>2025-Tue-P1001-P012</p> <p><i>Manuscript ID: 0075</i></p> <p><b>The Photonic Field Distribution Study of InGaN-based U-shape Micro LEDs</b></p> <p>Yi-Chia Hwang, Ke-Hsi Chiang, Yu-Long Zhong, Yu-Hsien Wen, Hao-Jen Chang, Chien-Chung Lin, Graduate Institute of Photonics and Optoelectronics, National Taiwan University</p>
<p>2025-Tue-P1001-P013</p> <p><i>Manuscript ID: 0078</i></p> <p><b>Dependence of hole concentration on the AlN mole fraction in polarization-doped AlGaIn without Mg doping on AlN</b></p> <p>Tepei Takehisa, Hibiki Muto, Sena Miura, Marina Fujita, Kenta Takase, Haruto Hirota, Hisanori Ishiguro, Motoaki Iwaya, Satoshi Kamiyama, Tetsuya Takeuchi, Meijo Univ.; Yoshiki Saito, Koji Okuno, Hiroshi Miwa, TOYODA GOSEI Co. Ltd.</p>
<p>2025-Tue-P1001-P014</p> <p><i>Manuscript ID: 0094</i></p> <p><b>The AlGaIn-Based Deep Ultraviolet Micro-Light-Emitting Diodes with Thermally Oxidized AlxGa2-xO3 Sidewall</b></p> <p>Tien-Yu Wang, Wei-Chih Lai, Qiao-Ju Xie, Jinn-Kong Sheu, Department of Photonics, National Cheng Kung University.; Sheng-Po Chang, Department of Microelectronics Engineering, National Kaohsiung University of Science and Technology.; Cheng-Huang Kuo, Institute of Lighting and Energy Photonics, College of Photonics, National Yang Ming Chiao Tung University.</p>

2025-Tue-P1001-P015

*Manuscript ID: 0111*

**Defect Control of p-GaN Cladding Layer in Red-emission Nanocolumn LED Crystals**

Mahiro Oguchi, Rie Togashi, Katsumi Kishino, Sophia University

2025-Tue-P1001-P016

*Manuscript ID: 0116*

**Low-temperature characteristics of GaN-based Ultraviolet Micro LEDs with ALD Passivation**

Yu-Hsien Wen, aabbcc112233445566778899@gmail.com; Yu-Long Zhong, a0903195247@gmail.com; Bo-Ming Huang, bomig30414@gmail.com; Yi-Chia Hwang, EricHwang@playnitride.com; Chien-Chung Lin, chienchunglin@ntu.edu.tw

2025-Tue-P1001-P017

*Manuscript ID: 0084*

**High temperature operation and temperature dependence of N-polar GaN/AlN HEMTs**

N. Okada, F. Yamanaka, A. H. Zazuli, M. Feng, T. Kimoto, R. Ninoki, N. Hirata, H. Danbata, A. Hayashiuchi, S. Kurai, Y. Yamada, Yamguchi Univ.; M. Hiroki, K. Hirama, Y. Taniyasu, Basic Research Laboratories, NTT, Inc.

2025-Tue-P1001-P018

*Manuscript ID: 0135*

**Monolithically Integrated AlGaIn/GaN HEMTs-Based CMOS Logic Circuits**

Pei-Yu Ling, aa82603053@gmail.com; Wen-Yao Yang, a0978103282@gmail.com; Yeong-Her Wang, yhw@ee.ncku.edu.tw; Lung-Hsing Hsu, algerhsu@narlabs.org.tw; Wen-Hsien Huang, whhuang@narlabs.org.tw; Kuan-Wei Lee, Department of Electronic Engineering, I-Shou University, Kaohsiung 840, Taiwan

# Special Session. Ultrawide-bandgap materials and devices

Oral Session: 2nd Lecture Room 第二演講室 (B1F)

Poster Session: Multifunction Room 多功能廳 (1F)

## Oral Session: 09:15-11:30, Wednesday, November 12, 2025

### Presider:

Prof. Hsin-Ying Lee (National Cheng Kung University, Taiwan)

Prof. Sheng-Po Chang (National Kaohsiung University of Science and Technology, Taiwan)

• 09:15 2025-Wed-S1105-I001

### Invited Talk

#### Nitrogen doping technology for Ga<sub>2</sub>O<sub>3</sub> devices

Prof. Masataka Higashiwaki, Professor, Osaka Metropolitan University, Japan

• 09:45 2025-Wed-S1105-I002

### Invited Talk

#### Recent Advances in Heteroepitaxial Diamond: From Single Crystal Substrate to Devices

Prof. Okhyun Nam, Tech University of Korea, South Korea

• 10:15 2025-Wed-S1105-O001

*Manuscript ID: 0032*

#### Phase Transformation and Ferroelectricity of $\epsilon(\kappa)$ -Ga<sub>2</sub>O<sub>3</sub>

Po-Kai Kung, Dong-Sing Wu, Department of Applied Materials and Optoelectronic Engineering, National Chi Nan University, Nantou 54561, Taiwan; Wen-Hao Lee, Department of Materials Science and Engineering, National Chung Hsing University, Taichung 40227, Taiwan; Tung-Han Wu, Po-Liang Liu, Graduate Institute of Precision Engineering, National Chung Hsing University, Taichung 40227, Taiwan

• 10:30 2025-Wed-S1105-O002

*Manuscript ID: 0063*

#### Effect of 2D carrier localization on light emission in (Al,Ga)N alloys emitting in the Deep UV range.

Alexandra Ibanez, Bernard Gil, Guillaume Cassabois, Pierre Valvin, Wilfried Desrat, UMR 5221, Laboratoire Charles Coulomb and Université Montpellier 2, Montpellier, 34095, France; Nikita Nikitskiy, Julien Brault, Mathieu Leroux, Antoine Barbier, Fabrice Semond, CNRS-CRHEA, Université Côte d'Azur, Valbonne, 06560, France; Muhammad Khan, Hideki Hirayama, Fumiya Chugenji, Taiga Kirihara, RIKEN Cluster for Pioneering Research (CPR), 2-1 Hirosawa, Wako, Saitama 351-0198, Japan

• 10:45 2025-Wed-S1105-O003

*Manuscript ID: 0072*

#### Ultra-Wide Bandgap AlGa<sub>N</sub> Polarization Doped PoIFET Heterostructures for RF Transistors with a Contact Resistance less than 1 ohm.mm

Andrew Allerman, Andrew M. Armstrong, Brianna A. Klein, Sandia National Laboratories, Albuquerque, NM, USA, 87185; Seungheon Shin, Yinxuan Zhu, Jon Pratt, Davide Orlandini, Siddharth Rajan, Department of Electrical and Computer Engineering, The Ohio State University, Columbus, Ohio, USA

• 11:00 2025-Wed-S1105-O004

Manuscript ID: 0039

**Investigation of Ga<sub>2</sub>O<sub>3</sub>-based NO<sub>2</sub> Gas Sensors with Roughened Seed Layer**

Ting-Chun Chang, Tun-Hui Yang, Hsin-Ying Lee, Department of Photonics, National Cheng Kung University, Tainan 701, Taiwan, Republic of China; Mu-Ju Wu, Program on Key Materials, Academy of Innovative Semiconductor and Sustainable Manufacturing, National Cheng Kung University, Tainan 701, Taiwan, Republic of China; Ching-Ting Lee, Institute of Microelectronics, Department of Electrical Engineering, National Cheng Kung University, Tainan 701, Taiwan, Republic of China

• 11:15 2025-Wed-S1105-O005

Manuscript ID: 0058

**Low interface trap density of 4H-SiC MIS capacitor with a boron nitride PECVD layer**

Ravi Ranjan Kumar, Promit Kumar Khan, Niall Tumilty, National Yang Ming Chiao Tung University

**Poster Session: 15:00~17:00, Tuesday, November 11, 2025**

2025-Tue-P1101-P001

Manuscript ID: 0001

**Atomic-Scale Characterization of Coherent  $\beta$ -Ga<sub>2</sub>O<sub>3</sub>/Al<sub>2</sub>O<sub>3</sub> Interface Formed by MOCVD**

Wei-Chun Chen, Wei-Lin Wang, Kun-An Chiu, Hung-Pin Chen, Yu-Wei Lin, Fong-Zhi Chen, National Center for Instrumentation Research, National Institutes of Applied Research

2025-Tue-P1101-P002

Manuscript ID: 0002

**Heteroepitaxial Growth of high-quality  $\beta$ -Ga<sub>2</sub>O<sub>3</sub> Films on c-Al<sub>2</sub>O<sub>3</sub> substrate with various O<sub>2</sub>/Ga flow rate by MOCVD**

Wei-Chun Chen, Wei-Lin Wang, Kun-An Chiu, Hung-Pin Chen, Yu-Wei Lin, Chao-Te Lee, Fong-Zhi Chen, National Center for Instrumentation Research, National Institutes of Applied Research

2025-Tue-P1101-P003

Manuscript ID: 0006

**Investigation of a diamond epitaxial layer with a gradient of Boron doping**

Thu Nhi Tran Caliste, Jose Baruchel, European Synchrotron Radiation Facility (ESRF); David Eon, Université Grenoble Alpes, Institut Néel, CNRS UPR2940, BP 166, Grenoble, F-38042, France;; Patrik Straňák, Lutz Kirste, Fraunhofer Institute for Applied Solid State Physics (IAF), Tullastrasse 72, Freiburg, D-79108, Germany

2025-Tue-P1101-P004

Manuscript ID: 0016

**Effect of Sapphire Substrate Orientation on the Performance of Enhancement-Mode  $\beta$ -Ga<sub>2</sub>O<sub>3</sub> MOSFETs**

Ching-Hsuan Lee, Wei-Jhe Chen, Ray-Hua Horng, Institute of Electronics, National Yang Ming Chiao Tung University, Hsinchu 30010, Taiwan, ROC

<p>2025-Tue-P1101-P005</p> <p><i>Manuscript ID: 0017</i></p> <p><b>Thermally Enhanced Dopant Activation in Non-Recess <math>\beta</math>-Ga<sub>2</sub>O<sub>3</sub> MOSFET Fabrication</b></p> <p>Chun-Chia Chang, Jun-Ting Ye, Institute of Electronics, National Yang Ming Chiao Tung University, Hsinchu 30010, Taiwan, ROC.</p>
<p>2025-Tue-P1101-P006</p> <p><i>Manuscript ID: 0023</i></p> <p><b>Impact of Schottky Metal Stacks on Electrical Performance of <math>\beta</math>-Ga<sub>2</sub>O<sub>3</sub> SBDs</b></p> <p>Cheng-Jhang Yu, taco012354@gmail.com; Zhong-Lin Ye, gary0612.ii12@nycu.edu.tw; Sheng-Ti Chung, shengti1985.c@gmail.com; Ray-Hua Horng, rayhua@nycu.edu.tw</p>
<p>2025-Tue-P1101-P007</p> <p><i>Manuscript ID: 0053</i></p> <p><b>Photoactivated CO Gas Sensor Based on <math>\beta</math>-Ga<sub>2</sub>O<sub>3</sub> Thin Films Deposited by RF Magnetron Sputtering</b></p> <p>Chun-Kai Wang, Department of Microelectronics Engineering, National Kaohsiung University of Science and Technology, Kaohsiung, Taiwan; I-Hsiung Wang, Yu-Zung Chiou, Department of Electronics Engineering, Southern Taiwan University of Science and Technology, Tainan, Taiwan</p>
<p>2025-Tue-P1101-P008</p> <p><i>Manuscript ID: 0077</i></p> <p><b>Thermodynamic and experimental studies of c-In<sub>2</sub>O<sub>3</sub> growth using In<sub>2</sub>O and H<sub>2</sub>O source gases</b></p> <p>Rie Togashi, Sophia University, Chiyoda, Tokyo 102-8554, Japan; Masato Ishikawa, Gas-Phase Growth Ltd., Koganei, Tokyo 184-0012, Japan</p>
<p>2025-Tue-P1101-P009</p> <p><i>Manuscript ID: 0083</i></p> <p><b>Fabrication of Indium Tungsten Gallium Oxide Thin Films for Application in Phototransistors</b></p> <p>Yu-Quan Zhang, Feng-Chi Liu, Zi-Zhen Wang, Wei-You Shen, Song-Jing Song, Ming-Chih Tsai, Yi-Cheng Lin, Sheng-Po Chang, National Kaohsiung University of Science and Technology; Yu-Chen Chen, National Cheng Kung University</p>
<p>2025-Tue-P1101-P010</p> <p><i>Manuscript ID: 0100</i></p> <p><b>Breaking Circular Polarization Symmetry via Chiral PB-Phase Metasurfaces</b></p> <p>Chih-Shan Chuang, m46144102@gs.ncku.edu.tw; Shih-Hsiu Huang, kitgun124@gmail.com; Po-Sheng Huang, louis19950128@gmail.com; Hsiu-Ping Su, samwii888@gmail.com; Pin Chieh Wu, pcwu@gs.ncku.edu.tw</p>
<p>2025-Tue-P1101-P011</p> <p><i>Manuscript ID: 0101</i></p> <p><b>Enhanced Efficiency in Visible Metalenses Using Complex Electric Field Optimization</b></p> <p>Po-Sheng Huang, Pin Chieh Wu, Department of Photonics, National Cheng Kung University</p>
<p>2025-Tue-P1101-P012</p> <p><i>Manuscript ID: 0123</i></p> <p><b>AI-driven Prediction Framework for High-Power SiC Trench MOSFET's Parameters</b></p>

Tejender Singh Rawat, Chia-Lung Hung, Yi-Kai Hsiao, Wei-Chen Yu, Surya Elangovan, Wei-Ting Lin, Hao-Chung Kuo, Semiconductor Research Center, Hon Hai Research Institute, Foxconn, Taiwan

## Poster Bulletin Board No.

(Please post according to the poster bulletin board number)

(請務必依照海報板編號張貼)

Poster Bulletin Board No.	Poster No.	Manuscript ID	Title
001	2025-Tue-P0101-P001	0071	<i>3D CFD Study of Internal Installation Geometry Effects on Convective Transport and GaN Crystal Growth in the Ammonothermal Process</i>
002	2025-Tue-P0101-P002	0093	<i>From Crystal to Wafer: Advanced Mechanical Processing of Ammonothermal GaN</i>
003	2025-Tue-P0101-P003	0102	<i>Properties of defects formed as a result of hillock coalescence in Am- and HVPE-grown GaN crystals.</i>
004	2025-Tue-P0101-P004	0105	<i>Thermodynamic Analysis of GaN Solubility in Supercritical Ammonia: Influence of Mineralizer Concentration and Pressure</i>
005	2025-Tue-P0101-P005	0011	<i>Bragg Diffraction Imaging Analysis of Crystal Defects in AlN Substrates</i>
006	2025-Tue-P0101-P006	0057	<i>Analysis of Growth Discontinuities in Ammonothermal GaN Crystals Using Bragg Diffraction Imaging</i>
007	2025-Tue-P0201-P001	0033	<i>Effect of Flux Composition on Growth Behavior of AlN Crystals Using Fe-Cr-Ni Fluxes</i>
008	2025-Tue-P0201-P002	0067	<i>Buffer Layer Design toward 1600 V GaN HEMTs on 150 mm Si Substrates</i>
009	2025-Tue-P0201-P003	0080	<i>Performance Enhancement of AlGaIn/GaN HEMTs on 150 mm Si Substrates by B<sub>0.2</sub>GaN Buffer Layers</i>
010	2025-Tue-P0201-P004	0113	<i>Direct growth of Bulk InGaIn nanocolumns on nanotemplates prepared using Ni nanodot mask</i>
011	2025-Tue-P0201-P005	0114	<i>Influence of Underlying GaN Nanocolumns on the Selective Area Growth of GaInN</i>
012	2025-Tue-P0201-P006	0115	<i>Surface Stoichiometry Control in GaN Pulsed Sputtering Epitaxy Using Sintered Target</i>
013	2025-Tue-P0201-P007	0124	<i>USPD-Fabricated Li-Doped p-NiO<sub>x</sub> Gates for High-Performance Normally-Off InAlGaIn/GaN HEMTs</i>
014	2025-Tue-P0201-P008	0134	<i>Growth and characterization of N-polar AlN and strained GaN heterostructures by MOVPE</i>

Poster Bulletin Board No.	Poster No.	Manuscript ID	Title
015	2025-Tue-P0301-P001	0091	<i>AlxGa1-xN growth by Halide Vapor Phase Epitaxy</i>
016	2025-Tue-P0401-P001	0005	<i>The Blood Test for Lung Cancer by InGaN Quantum Wells</i>
017	2025-Tue-P0401-P002	0097	<i>Growth of Boron Nitride on (100) Silicon Substrates</i>
018	2025-Tue-P0401-P003	0054	<i>Coupling between WSe2 and Plasmonic Structure</i>
019	2025-Tue-P0401-P004	0052	<i>Formation of non-polar and semi-polar AlN planes via microwave annealing of AlN on AAO templates</i>
020	2025-Tue-P0401-P005	0076	<i>Sensitivity Enhancement of Aluminum Nitride Surface Acoustic Wave Humidity Sensors Using Silica Nanospheres</i>
021	2025-Tue-P0501-P001	0035	<i>Comparison of n-Ga<sub>2</sub>O<sub>3</sub>/p-GaN PN Heterojunction Diode Grown by TMGa and TEGa</i>
022	2025-Tue-P0501-P002	0036	<i>Effect of Post-Deposition Annealing on Room-Temperature Sputtered NiO Gate Dielectric for AlGaIn/GaN HEMTs</i>
023	2025-Tue-P0601-P001	0021	<i>The performance comparison of GaN vertical transistors with sidewalls treated using TMAH and H3PO4 solutions</i>
024	2025-Tue-P0601-P002	0044	<i>Study on the Growth Mechanism of Periodic Structure MoS<sub>2</sub></i>
025	2025-Tue-P0601-P003	0045	<i>Fabrication of Cu<sub>2</sub>O Biosensor for Photoelectrochemical and Impedance Detection of Lung Cancer Cell</i>
026	2025-Tue-P0601-P004	0055	<i>Fermi Level Pinning behaviour of semi-polar (10-11) n-GaN surface before and after passivation</i>
027	2025-Tue-P0601-P005	0082	<i>Vacancy defects in III-nitride alloys</i>
028	2025-Tue-P0701-P001	0034	<i>Investigation of (Al,Ga)N:Mg p-type doping using UV light excitation during molecular beam epitaxy growth</i>
029	2025-Tue-P0701-P002	0050	<i>Photon Recycling-Driven Vertical Light Extraction in InGaIn Nanorods for Advanced Micro-LED Efficiency</i>
030	2025-Tue-P0701-P003	0069	<i>Open-Circuit Voltage Methods to Detect Micro-LED Characteristics</i>
031	2025-Tue-P0701-P004	0121	<i>Thickness-Dependent strain relaxation in Semipolar (11-22) AlN on m-Sapphire</i>
032	2025-Tue-P0801-P001	0038	<i>Optical Gain Evolution and Field Screening in Wide Polar InGaIn and AlGaIn Quantum Wells</i>
033	2025-Tue-P1001-P001	0004	<i>Directional Optimization of Resonant Cavity Micro Light-Emitting Diodes Using Multilayer DBR and Microlens Integration</i>

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035	2025-Tue-P1001-P003	0014	<i>Tunnel Junctions for New Architecture of Nitride Devices</i>
036	2025-Tue-P1001-P004	0015	<i>Observation of Quasi-Saturation in Sidewall-Gate GaN Vertical Transistors</i>
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# Memo



# Memo





台灣真空學會  
Taiwan Vacuum Society



# 真空技術研討會暨 理論與實務/操作全系列訓練班

日期:2025年12月18-19日  
課程地點:高雄市-國立中山大學

課程大綱	講師/現職
真空度量—儀表、量測與校正/測漏與封合	陳維鈞/國家實驗研究院國家儀器科技研究中心智慧鍍膜設備發展組 研究員兼任組長
真空技術基礎與系統工程綜述/真空系統	熊高鈺/國家同步輻射研究中心 研究員
材料與真空元件/真空幫浦	薛心白/國家同步輻射研究中心 助研究員
真空系統組裝封合→抽氣→測漏→補漏與拆解/ 成果報告	資深真空工程師 班主任—林煒淳/國立中山大學光電系 副教授

(1) 一天課程:基礎課程、進階課程二擇一,新台幣 3,500 元。  
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凡台灣儀器科技研究中心同仁、台灣鍍膜科技協會會員,均屬學會會員價



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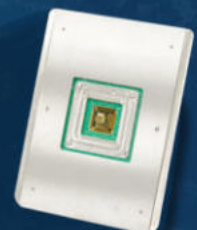


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## 電子束直寫系統

Ultra High Resolution E-beam Writer  
CABL-UH130/UH110E



CABL-UHPoint Beam

- V<sub>acc</sub>: 130kV Max
- Min. Beam Dia.: 1.6nm
- Min. Line Width: 7nm
- Field Size: ≥ □1000μm

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FIB-DB550



- 低壓高分辨電子鏡筒
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- 集成式納米機械手
- “承影”商子鏡筒
- 集成式氣體注入器
- 快速換樣倉(最大8寸)

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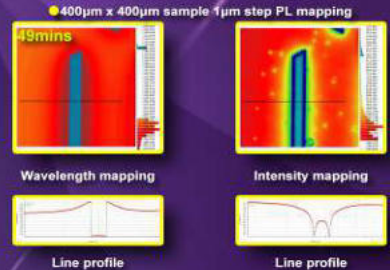
MOCVD Retrofit



- 中古MOCVD買賣、維修
- Planetary & CCS MOCVD
- 管線增減、加熱帶、流量控制閥/ 壓力控制閥變更
- 管線清潔、磊晶尺寸變更、模組修復、備件買賣維修

## 光致螢光光譜儀

PLATO-MicroScan: Micro PL for InP based LD



## 灰階/直寫曝光系統

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- 高速描畫
- 3D曝光
- 最大曝光領域 □300mm
- 與曝光光學系統作同軸觀察



## 感應耦合電漿蝕刻機

● DRIE Etcher

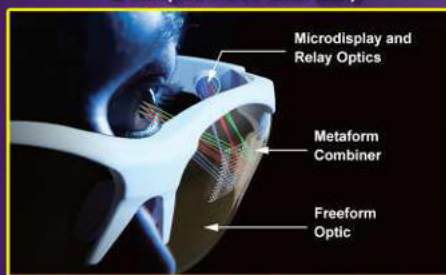
● ICP Etcher (Non-metal)

● ICP Etcher (Metal)



## AR/VR Nano Imprint

● XR (AR/VR Market)



## 高溫無塵無氧烘箱

高溫●無塵●無氧

- CLASS 100 (option: class 10)
- TEMP: 300°C (option: Max 500°C)
- UNIFORMITY: ± 1.5%
- Oxygen content : 50ppm



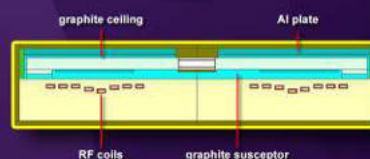
## 3D圖形化原子層鍍膜

DIRECT ATOMIC LAYER PROCESSING

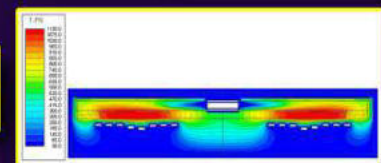


## 磊晶模擬軟體

- 化合物半導體MOCVD模擬
- VR Nitride/ IIIV



AIN MOCVD 8x150mm & 5x200mm行星式反應腔



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82CWW Series dual-mode hybrid bonding equipment

82 CWW Application

## MAIN PRODUCTS

### 晶圓鍵合設備系列

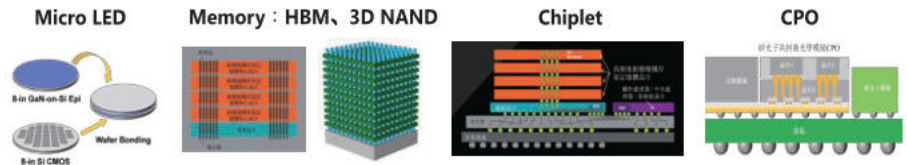
Wafer Bonding Equipment Series

### 晶圓/晶片混合鍵合設備系列

W2W/C2W Hybrid Bonding Equipment Series

### 表面處理設備系列

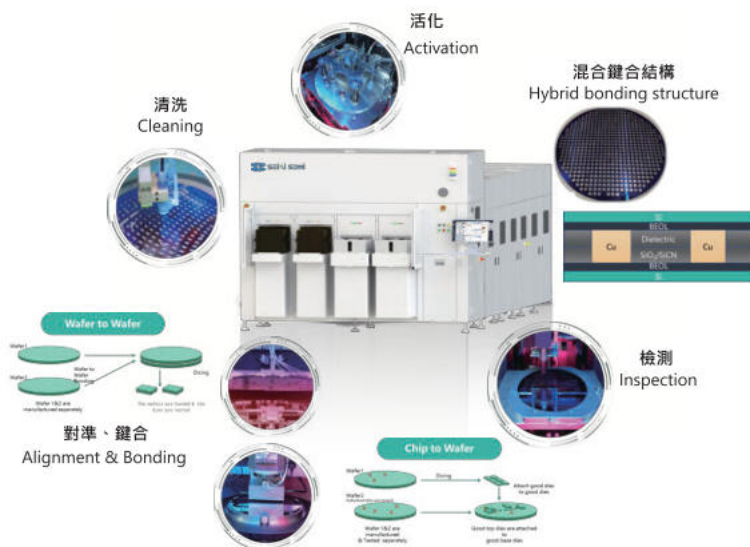
Surface Treatment Equipment Series



Our OEM Service: SiC-SiC, LTOI, LNOI, SiCOI, SOI, Si-SiC...



Seiki Semiconductor founded in Japan and based in Taiwan



## ABOUT US

- Over 20 years of expertise in developing hybrid bonding equipment and processes for advanced packaging.
- Technologies applied in memory chips, CMOS image sensors, Micro-LED displays, silicon photonics, and wafer-level heterogeneous integration.
- Provides OEM bonding services for the semiconductor manufacturing industry.



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Seiki Semiconductor Co., Ltd.

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**Mail :** jorgen.yeh@seikisemi.com  
**TEL :** +886 35973325 #3382  
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# PLASMA PROCESS EQUIPMENT

Samco specializes in deposition, etching, and surface treatment, driving cutting-edge research and device production.

## PRODUCTS

## WHO WE ARE


Established in 1979, Samco began as a garage start-up in Kyoto, aiming to provide cutting-edge semiconductor and electronic component manufacturing systems globally. Over time, it has evolved into a leading global corporation with state-of-the-art technological capabilities and a widespread presence. Our commitment to growth prioritizes "thin-film technology" as our core expertise.



**DEPOSITION**

- ALD
- PECVD
- Liquid Source CVD


AD-800LP



**ETCHING**

- ALE
- Si DRIE
- RIE (ICP-RIE, CCP-RIE)
- XeF<sub>2</sub>

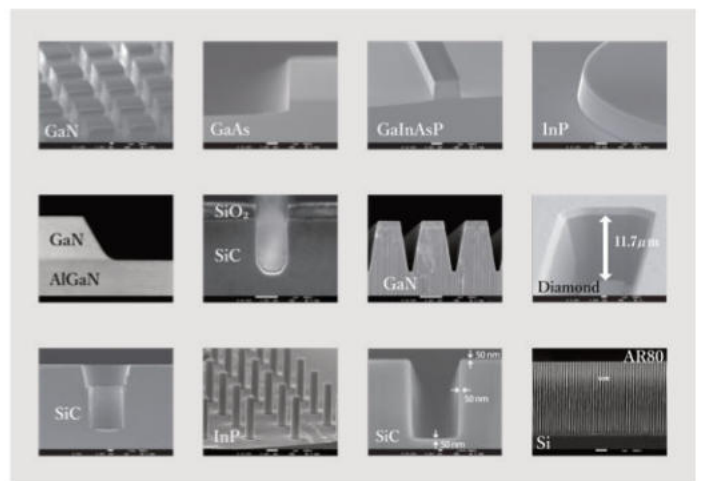
RIE-800IPC



**SURFACE TREATMENT**

- Aqua Plasma
- Plasma Cleaning
- UV Ozone Cleaning

AQ-2000



# SENTECH

Erfolg durch Leistung

## Etching

- SI 500
- Etchlab 200, SI 591

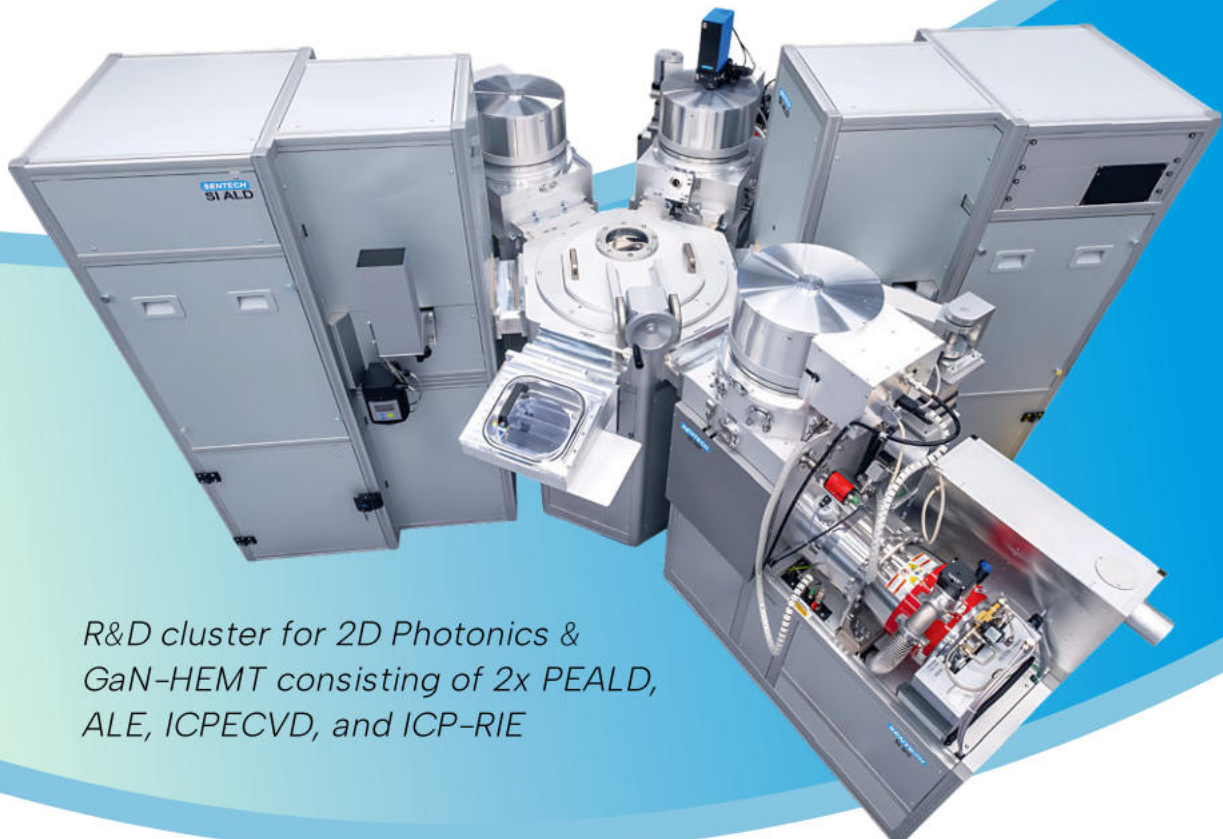
## Deposition

- SI 500 D
- DEPOLAB 200
- SI PEALD

## SENTECH Plasma Systems

Etch & deposition for

- Optoelectronics
- Microoptics
- MEMS
- Microelectronics
- RF/power devices
- III-V Semiconductors
- 2D Materials
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歡迎立即聯繫我們

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# NeoDry G-SERIES

NeoDry7G  
NeoDry15G  
NeoDry30G  
NeoDry36G

**NEW  
RELEASE**



**Maintenance cycle;  
Once in 6 years!**  
(Approx. when Air/N<sub>2</sub> is used)  
\*Based on our track record of sales.

-  **Wide Voltage Range!** Switchable between 1ph 100V and 200V automatically.
-  **Quieter & Temperature Optimization!** Typically 45dB (51dB for 36G) at ultimate pressure. Optimized pump temperature with fan control.
-  **Water vapor evacuation performance upgraded!** Gas ballast enables the vacuum of condensable gases and brings a 10% water vapor evacuation performance boost. (Except 36G)
-  **IEC Power Connector!** IEC connector adopted for your convenience.
-  **Meet Harmonic Standards!** Meeting European harmonic emission requirement.
-  **Serial Communication Port!** Available for data communication and speed control with RS485 port

### Propel™ R&D

Faster cycles of learning for GaN-on-Si R&D

#### Accelerate to the Next Level with Veeco's Enhanced Small-Batch GaN MOCVD System

- Outstanding film uniformity, yield and device performance
- TurboDisc® technology features long campaign runs for process development flexibility and best-in-class low defectivity
- Modular design for ease of configuration, operation and maintenance



### Propel™ 300

Leading 300mm MOCVD System for GaN-on-Si

#### Enabling GaN-based Power and MicroLED devices with:

- Best-in-class thickness and doping uniformity
- Long campaigns with excellent repeatability
- High throughput and yields
- Low operating costs
- Proven track record at industry-leading fabs

### Veeco MBE Systems

Cutting-edge compound semiconductor materials

#### Enabling the highest quality epitaxial films for emerging technologies with:

- Superior process control
- Precision growth for Quantum Materials
- Flexible system architecture for R&D and high-volume manufacturing customers
- Configurable for different applications
- Best-in-class cost of ownership

